# P9000 Cluster System User Manual



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P9000 Cluster System User Manual

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# *Contents*

CHAPTER 1	Introduction 1
	Chapter Outline 1
	Product Overview 2
	Key Features 2
	P9000 Operating Console <b>3-4</b> <i>Top Panel</i> <b>5</b> <i>Workspace</i> <b>6</b> <i>Navigation Bar</i> <b>7</b>
	System Setup Procedures 8
	Product Safety 8-9 <i>Emergency Shut Down</i> <i>System Start Up</i> <i>System Shut Down</i> Technical Support 10
	Product Decumentation 10
	Product Documentation 10
CHAPTER 2	Operator's Guide 11
	Chapter Outline <b>11</b> P9000 Operational Requirements <b>12</b>
	System Turn On/ Log in the P9000 operating console 12 Main Page Workspace UI components 13
	Wafer-Processing Operation Procedures 14
	Managing System Operations 14 Resetting the System 14 Clearing the System 15 Confirming Wafers 15
	Dealing with Alarms/Table 15
	Module-Specific Controls 19

CHAPTER 3	Configuring Programs & Recipes 20
	Chapter Outline 20
	Recipes and Programs 21
	Accessing the Recipes Page 21
	General Procedures for Recipe Creation 22
	Managing Arm Programs 23 Creating a New Arm Program 2325 Dispense Arm Operations and Measurement 26 Modifying an Existing Arm Program 27 Deleting an Existing Arm Program 27 Exporting Arm Programs 28 Importing Arm Programs 29 Sharing Arm Programs 20
	Sharing Arm Programs 30
	Managing Fump Programs31Creating a New Pump Program31-32Modifying an Existing Pump Program33Deleting a Pump Programs34Exporting Pump Programs34Importing Pump Programs35Sharing Pump Programs36
	Managing Module Programs <b>37</b> Creating a New Module Program <b>37-</b> 40 Editing Existing Module Programs 41 Deleting Module Programs <b>42</b> Exporting Module Programs <b>42</b> Importing Module Programs <b>43</b> Sharing Module Programs <b>44</b>
	Managing Recipes 45 Creating New Recipes 45-48 Modifying an Existing Recipe 49-51 Deleting an Existing Recipe 52 Exporting Recipes 53 Importing Recipes 54 Sharing Recipes 55
	Managing Module Options 57 Accessing the Module Options Page 57 Viewing a Module's Options 58 Modifying an Option Value 59

#### System Setup 60 **CHAPTER 4** Chapter Outline 60 P9000 System Setup 61 Customizing P9000's General Settings 61 Enable/Disable Modules 62 Sharing Modules 62 Processes 62 **Configuring Network Communication** 63 Performing Remote Component Exercise 64 Customizing Pump Settings 65 Accessing the Pump Settings Page 65 Creating New Pump Controllers 66 Adding Pumps to a Pump Controller 67-68 Linking Pumps to Modules 69-71 Managing Users 72 Opening the Manage User Page 72 About the User Management Page 73 Creating and Defining User Roles 73 Modifying User Roles 74 Deleting User Roles 75 Creating User Accounts 75 Modifying User Accounts 76 Deleting User Accounts 77 **Configuring System Messages** 77 Modifying Existing Messages 78 Creating New Messages 78 Miscellaneous Configurations 78 Setting Up Marathon Tests 79 Managing Data Logs 79 Miscellaneous Settings 79 Viewing & Managing Reports 80 **CHAPTER 5** Chapter Outline 80 Access the Datalog Page 81 Types of Reports 81

Datalog Page UI Components82Alarm Reports83Event Reports84Wafer Lost Reports86User Reports87Batch Reports88Batch Details Reports89

System Maintenance

#### **CHAPTER 6**

Chapter Outline 91 System Calibration 92 Robot Arm Positions 93 Robot-Indexer Position 93 Robot-Indexer Scan Position 94 Robot-Mechanical Centering Pickup Position 95 Robot-Centering Pickup Position 96 Robot-Coater Position 96 Robot-Developer Position 97 Robot-Chill Plate Position 98 Robot-Hot Plate Oven Position 99 Robot-Vapor Prime Position 100 Backing Up and Restoring Robot Configuration 101 Backing Up Robot Configuration 101 Restoring Robot Configuration 104 Testing the Robot After Restore 106 Centering Coaters/Developers 107 Centering Chill Plates 109 Centering the Hot Plate Ovens 111 Centering the Mech Centering 112 Calibrating the Centering 114 Calibrating Support-Pin Height 114 **Checking Vapor Prime Operations** 116 Checking Hot Plate Oven Exhaust 118 Checking Coater/Developer Exhaust with Controller 118

91

Checking Coater/Developer Exhaust without Controller 119 Checking Coater/Developer Low Spin Speed 119 Checking Coater/Developer High Spin Speed 121 Checking the Developer Air Ring Gap 122 Checking Hot Plate Oven/Vapor Prime Temperature 123 Calibrating the WATLOW 124

Appendix A Hazardous Energies Appendix B System Interlock Table Revisions This page is intentionally left blank.

# CHAPTER 1 Introduction

# Chapter Outline

This chapter discusses P9000's main features, hardware components, operating console, and system setup procedures. It covers the following topics:

- Product overview
- Key features
- P9000 operating console
- System setup procedures
- Product safety
- Technical support
- About this User Guide

# **Product Overview**

The P9000 is a high-throughput, multi-purpose, wafer-processing system that can be configured as a coater, developer, vapor primer, baker, chiller, etc., or a combination of all the aforementioned and is capable to process a wide range of photoresist and photosensitive polymer applications. Its sophisticated system software, along with its state-of-the-art hardware, allows the operator to process hotplates at various bake temperatures, and prime, coat, and develop wafers in parallel according to pre-configured recipes. The system is easily scalable to keep pace with business growth and changing production requirements.

# Key Features

The P9000 comes with the following key features:

- Powerful, intuitive application software makes the system easy to program and operate.
- Recipe-driven, automated system operation ensures operation efficiency, high productivity, consistency, and quality.
- Ability to process 50mm-200mm substrates without hardware changeover.
- Dual-cassette indexers able to support two parallel recipes at the same time.
- A hardened, reliable automated system also supports manual operations.
- A central atmospheric robot with dual-end effector -high-volume processing and wafer temperature sensitivity.
- A stackable station design dramatically saves floor space.
- CE certification ensures compliance with European Union (EU) requirements.
- Semi S2 certification ensures the Safety Guidelines for Semiconductor Manufacturing Equipment

#### **Facility requirements**

Electrical	
Power	208V
Phase	3Φ
Frequency	50 - 60 Hz
Current	25A
AIC	5000 A Interrupt Rating

Physical	
System Foot Print	3.79ft length x 4.79ft wide x
	6.25ft height
System Weight	1800LBS
Vacuum Pressure	22-25 in Hg/
Fuse/Circuit Breakers	Appendix A
System Interlocks	Appendix B

NOTE: P9000 Systems are custom, each System Layout Drawing contains the appropriate resource information for individual Facility Requirements. It is highly recommended each customer use the Facility Layout Drawing, Preventive Maintenance and Users manuals when familiarizing themselves with the P9000 System prior to commencing use.

P9000 Operating Console

The P9000 operating console is the system's graphical user interface (GUI) by which the operator interacts with the system. This section provides a detailed discussion about each of the components of the P9000 operating console. It is highly recommended that the operator should familiarize him- or herself with these components before starting to operate the system.

Figure 1-1 highlights the major sections of the P9000 operating console user interface. For ease of reference, we mark each section with a reference number. Detailed discussions about each of these sections are provided in the following paragraphs.

CBD SmartPro P9000 -	Version 2.1.1742.	93 (iCore.Multiwa	afers - New Algorithm)			
CED	Connected	11/04/2013	@smartPro P	9000  🖳 🖁	me: Admin le: Administrator	😑 System Idle
	Court, U	4.0023 FM	1	Log On: 0	000:00:50:15	Transfer Stop
Processes 10 RE	CIPE1:			G RECIPE2:		
Station 4 (O. U. Z. II	Station	5 (X 0,1,2,3,4) Chill5	Station 6 (J. K. L)	Double check empty slots	Memo	Memo
Hpo1			Hpo4	C Reset System	(III) Select Recipe	(iii) Select Recipe
Mech. Centerin		Chill4	Hpo3		Start Process	Start Process
VPrime		Chill3	Han?		Cassette 1	Cassette 2
		Chill2		Map wafers		
Station 3 (E, G)		Charl	Station 7 (F, H)	C Reset		19 18 17
Oev1		Cimit	Sev2		15 14 13	15 14 13
Coater1		Robot	Coater2		11 10 9	10 9
		n 1: n 2: ment:		J	9 7 6 5	
St	ation 2 (B, T, D)	Station	Indexer2	Transfer Stop		4
	Mapped: 0 wafers		apped: 0 wafers	() Clear System	Manual Select	Manual Select
🙆 Main 🍾	System 🧹	Recipes	Data	Setup 🔒 Alarms	Silence	😢 Help
			(3)			

FIGURE 1-1: P9000 console graphical user interface

- 1. Top panel
- 2. Workspace
- 3. Navigation bar

#### **Top Panel**

The top of the P9000 operating console displays some general information about the system's current operating status. Figure 1-2 highlights the major items of the P9000 operating console's top panel.



FIGURE 1-2: P9000 Operating Console Top Panel

Table 1-1 briefly describes the various components of the P9000's top panel.

UI Component	Description
Connection Status S	shows the connection status between the system's software and hardware (via the firmware), which can be either of the follow- ing:
	Connected
	• Disconnected
Wafer Count	Indicates the total number of wafers the system has processed.
Date & Time	Shows the current date and time.
User Information	Shows the name and role of the current user, as well as the length of time the user has been operating the system for the current session.
System Status	Shows the system's operating status which is indicated by the color of the dot and the words in the text field next to it.
	<b>Note:</b> The words in the text fields vary, depending on the page being selected as well as the system's operating status. See the following chapters for more information.

**TABLE 1-1:** P9000 Operating Console Top Panel UI Components

#### Workspace

The middle section of the P9000 operating console is the workspace. Its content changes with the system page being opened. Figure 1-1 shows the look and feel of the Main page. For more information about this part of the P9000 GUI, see the following chapters.

#### **Navigation Bar**

The navigation bar contains buttons that allow you to navigate through the system's main pages. Clicking a button opens its corresponding page. It's important to note that access to these main pages is determined by a user's role and privileges granted by the system administrator. Figure 1-3 illustrates the navigation bar.



FIGURE 1-3: P9000 System Navigation Bar

Table 1-2 briefly describes the navigation buttons and their related main pages. For more information about the main pages, see the following chapters.

Menu	Description
Main	Opens the Main page where the operator performs wafer-processing operations. By default, the Main page opens after you have logged into the system, as shown in Figure 1-1.
	<b>Note:</b> For information about the Main page and instructions on how to perform wafer- processing operations on the page, see Chapter 2.
System	Opens the System page where the system administrator or a qualified technician can configure and calibrate the various modules of the system.
	<b>Note:</b> For information and instructions about system configuration, see Chapter 3.
Recipes	Opens the Recipes page where the system administrator or a qualified technician can create and manage recipes that the operator can use to process wafers.
	<b>Note:</b> For information and instructions on how to create and manage recipes, see Chapter 4.

 TABLE 1-2: P9000 System Navigation Buttons

Menu	Description					
Datalog	Opens the Datalog page which contains various reports the system has generated.					
	<b>Note:</b> For information and instructions on how to view and manage system reports, see Chapter 5.					
Setup	Opens the Setup page where the system administrator or a qualified technician can set up the system. Below are some of the tasks for setting up the system:					
	• Enabling or disabling system modules					
	• Configuring system networking settings					
	Performing remote component exercise					
	Managing user accounts					
	Configuring pumps					
	• Performing system diagnostics					
	Configuring system messages					
	Configuring miscellaneous settings.					
	<b>Note:</b> For information and instructions on how to perform the above- mentioned tasks, see Chapter 6.					
Silence	Silences an ongoing system alarm, i.e., making it inaudible.					
	<b>Note:</b> Silencing an alarm only makes it inaudible; it does not solve the problem that triggers the alarm. The operator must read the error message to troubleshoot and resolve the problem. The alarm light will continue flashing until the error is cleared.					
Help	Opens the Help page where the operator can view a copy of this <i>User Manual</i> .					

#### TABLE 1-2: P9000 System Navigation Buttons

# System Setup Procedures

Before putting the P9000 into production, the system administrator or qualified technician must set up the various components of the system. The following are the procedures we recommend for setting up the system prior to putting it into production:

- 1. Make sure that there are no wafers sitting on any module in the system. Remove them if otherwise.
- **2.** Ensure that the power cord from the main control enclosure is plugged into a grounded power outlet. In addition, some installations may even require that the circuit breaker at a customer-supplied panel be switched on.
- 3. Power up the computer.
- **4.** Wait until the computer fully boots up. (*Note: It may take a few minutes for the system to fully boot up.*)
- 5. Turn on the power to the system.
- 6. Wait until the automatic system check completes to ensure that the system is ready to function. (*Note: The system automatically starts the system check which may take a couple of minutes to complete.*)
- 7. Create user accounts and assign roles.
- 8. Configure programs and recipes.
- 9. Put the P9000 into production. See Chapter 2.

# Product Safety /Definitions & System On/Off

The P9000 is powered by high voltages and uses potentially hazardous chemicals. It is housed inside a chamber made of stainless steel to prevent the operator from exposure to these hazards during normal system operation and maintenance. Hardwired interlocks, programmable process alarm conditions, covers, and other safety safeguards are provided wherever required to protect the operator from harm. Refer to Appendix A for instructions on the safe shut down of hazardous energy sources and the elimination of any solid waste contained as a result of processing activities. Refer to Appendix B for table of System Interlocks.

**EMO-** fail <u>safe control</u> switch or <u>circuit</u> that, when de-energized, will stop the <u>operation</u> of associated <u>equipment</u> and will shut off potential hazards outside the main power <u>enclosure</u>. Depressing the Manual EMO actuator will de-energize the P9000 System's Spindle Controller, Watlow Heaters, MCE Box and the Systems Computer. Following an EMO Shut Down; Reset the MCE Box first by switching to "ON", immediately followed by Power Reset of the Green Power Button. Refer to Resetting the System Section to continue at the systems Computer

**Green Power Button**: Depressing the Green Power Button in a Power Down situation will shut off the power to the DC Power Box and halt the module functions. Restarting the system if only from a Power Down can be facilitated by utilizing the Green Power On button. Refer to "Resetting the System" Section to continue reset at the systems Computer

**Interlocks** - a device that prevents you from making an inappropriate maneuver, or adjusts the system to a safe state if you make an inappropriate maneuver. The P9000 is equipped with Interlocking devices;

**Seismic Anchoring** –method of securing a system to protect from or pertaining to, an earthquake or vibration of the earth, Seismic anchors are System option on the P9000 Cluster System, it is the responsibility of the End User to provide adequate seismic anchors.

**Exhaust** -To drain, metaphorically; to use or expend wholly, or till the supply comes to an end. The P9000 System is designed with internal exhaust, supporting module activity. Dampers are present to control the flow of exhaust for dedicated modules. An audible alarm will sound should the exhaust go below its established set point (Ref. Appendix B, System Interlocks). System facility exhaust flow requirements are suggested and must be verified at End Users site.

The operator must strictly adhere to the operating and maintenance procedures at all times to prevent potential hazards or injuries. Under no circumstances should this system, including its electrical wiring, be altered or modified in any manner or by any means. Modifying the system, its wiring, otherwise overriding the hard- wired interlocks, or failure to follow the operating procedures defined in the product documentation could cause damage to the equipment and bodily injuries or even death

### **CAUTION**

#### TO ENSURE SYSTEM AND PRODUCT SAFETY, IT IS CRITICAL A WAFER BE ON THE CHUCK WHEN DISPENSING LIQUID AND AIR RING PRESSURE MUST BE VERIFIED TO SPECIFICATION

WARNING: In case of an emergency situation, immediately stop the system by pressing the red (EMO) emergency stop actuator on the P9000 System..

ONLY WELL-TRAINED PERSONNEL SHOULD OPERATE OR MAINTAIN THE SYSTEM. LACK OF KNOWLEDGE OF OR UNFAMILIARITY WITH THE OPERATING AND MAINTENANCE PROCEDURES COULD RESULT IN BODILY INJURIES OR EVEN DEATH.



For more information about product safety, refer to the master product documentation provided by the hardware manufacturer!

## Technical Support

We provide product technical support to our customers around the world. For technical support, visit our web site at http://www.cdsemi.com/contactus.html.

## **Product Documentation**

This *User Manual* mainly covers P9000's operating console which is the software portion of the system.

# CHAPTER 2 Operator's Guide

# **Chapter Outline**

This chapter discusses the general operating procedures an operator should follow when operating the P9000. It covers the following topics:

- P9000 operational requirements
- System Turn On/ Log into the P9000 operating console
- Main page workspace UI components
- Wafer-processing operation procedures
- Managing system operation
- Dealing with alarms
- Module-specific controls

# P9000 Operational Requirements

Normally, an operator is required to have the following in place in order to operate the P9000:

- A user account with valid user name and password
- Programs and recipes

It is the system administrator's responsibility to set up user accounts and create programs and recipes.

# Logging into the P9000 Operating Console

As an operator, you can start the P9000 using the following procedures:

- 1. From the desktop of the P9000, click the P9000 software icon. The P9000 login page opens.
- 2. Enter your user name and password, and press **Login.** The P9000's Main page opens.

# Main Page Workspace UI components

The Main page contains all the tools the operator needs to operate the P9000, as shown in Figure 2-1.



- 1. Processes Displays all modules available on the P9000. (*Note: The P9000 is a custom-built system. The types of modules and the number of units of a specific type of module may vary, depending on customer contracts.*)
- 2. Cassettes Displays the two cassettes on the P9000.
- **3.** System Controls Displays buttons used to control the operation of the whole system.
- 4. Module-Specific Controls Displays buttons used to control the operation of the currently selected module.
- 5. Recipe Information Displays the names of the recipes used in the current session.

# Wafer-Processing Operation Procedures

You can follow the instructions below to perform a wafer-processing operation:

- 1. Load wafers into a cassette.
- 2. Place the cassette of wafers on the Indexer station you intend to use.
- **3.** Identify the Indexer with the Cassette on the P9000 UI.
- 4. Click Get Recipe. The Download Recipe dialog box opens.
- **5.** Select the recipe you intend to use and click **Download.** (*Note: Information about the selected recipe shows up in the Recipe Information area on the top of the work space once the recipe has been successfully downloaded.*)
- 7. Click Start Process.
- **8.** If you want to run two processes simultaneously, place another cassette of wafers on the other Indexer station and repeat Steps 3 through 7.

# Managing System Operations

As a recipe-driven wafer-processing system, the P9000 automatically performs wafer-processing operations according to the selected recipe. Once a session starts, little effort is required of the operator. However, it does needs the operator's attention when an incident occurs which will trigger the alarm. In that case, the operator can use the instructions in the following sections to troubleshoot and resolve the issues.

#### **Resetting the System**

Each time you have powered up the P9000, you need to press the **Reset System** button so that the system application software can communicate to all modules and initialize them. You must do this before selecting a recipe.

You may also need to reset the system when the P9000 operating console (i.e., the GUI) lost connection to the modules. In this situation, clicking the Reset System button enables the software to reconnect with the modules.

#### **Clearing the System**

If a power outage occurs while a session is in progress, the system software and the modules will be disconnected. As a result, the session will be interrupted, leaving wafers on the stations. Once power is restored and the system is back on, the first thing you need to do is press the **Clear System** button. This will let the system check through all stations for wafers left in/on them and put them back into the cassette, clearing the way for you to resume the session.

Note: The only station the P9000 system does not check through is the Centering tool as the action is a momentary or temporary presence therefore it is not recognized. Wafers should be manually checked at this module following a power outage.

#### **Confirming Wafers**

At the start of each session, the Robot automatically scans all slots in the cassette for wafers and marks the result on the Cassette: slots with wafers are labeled "Present" and those without wafers show up blank. However, there are times when the sensor may fail to detect wafers in some slots even though they are present.

This is where the Wafers Confirmation check box comes into play. If selected, this feature will enable the Robot to go through all slots, including the vacant ones, during the operation. If it detects wafers in those initially vacant slots, the Robot will pick up them up for processing and mark the slots as "Present" at the same time. Without checking the Wafers Confirmation check box, the system will skip all slots that come up "empty" even though there are wafers in them.

## **Dealing with Alarms**

In the course of a session, the alarm will sound whenever the system encounters a problem. If that happens, you must first click the **Silence** button on the navigation bar to turn off the audible alarm. You should then read the error message on the screen to understand the nature of the error. Troubleshoot and resolve the issue if you can and seek assistance from a qualified technician if necessary. Reference the table provided here for Alarms and their associations.

#### Note:

Clicking the Silence button only turns off the audible alarm, but does not make the problem go away. You must resolve the issue that triggers the alarm before you can continue with the session.

				COA	FER / DEVEI	OPER				
				0011		State				
Code	Message	Not allow to start new lot	Not send any more wafers from cassette	Not accept next wafer	Stop processing wafer in current process		Audible alarm	Red light	Yellow light	Yellow light flashing
75	Drain high?		х	х			Х	х		
79	EBR level low?		х	х			х	х		
83	Level Sensor 1 low?		х	x			Х	х		
84	Level Sensor 2 low?		х	x			х	х		
85	Level Sensor 3 low?		х	x			х	х		
86	Level Sensor 4 low?		х	x			х	х		
125	Level Sensor 5 low?		х	x			х	х		
126	Level Sensor 6 low?		х	x			х	х		
161	Level Sensor 7 low?		х	x			х	х		
98	Coolant temperature out?		х	х			х	х		
100	Coolant Fluid level low?		х	x			х	х		
104	Exhaust out of band?						х		х	
151	Leak sensor on?	х	х	х			Х	х		
71	Cover open?			х	(by firmware)		X	х		
153	Chemical 1 low warning?	x					Х			х
154	Chemical 2 low warning?	x					Х			х
155	Chemical 3 low warning?	x					Х			х
156	Chemical 4 low warning?	х					Х			х
					HPO / ALLO	Y				
		NT .	NT .	NT .	a.	State		<b>D</b> 1	37 11	37.11
Code	Message	Not allow to start new lot	Not send any more wafers from cassette	Not accept next wafer	Stop processing wafer in current process		Audible alarm	Red light	Yellow light	Yellow light flashing
	Temperature out of band?		х	х			х	х		
	Heater over temperature?		х	х			х	х		

#### ALARM TABLE

Mp9000 Cluster System User Manual

				1	VAPOR PRIN	Æ				
						State				
Code	Message	Not allow to start new lot	Not send any more wafers from cassette	Not accept next wafer	Stop processing wafer in current process	Abort current processing wafer	Audible alarm	Red light	Yellow light	Yellow light flashing
	Temperature out of band?		х	x			х	х		
	Heater over temperature?		х	x			х	х		
	HMDS low level?		х	х			х	х		
	HMDS flow low?					(by firmware)	х	х		
SYSTEM										
						State				
Code	Message	Not allow to start new lot	Not send any more wafers from	Not accept next wafer into coat	Stop processing wafer in current process bowl	Stop robot transfer	Audiblealarm	Red light	Yellow light	Yellow light flashing
10	System air		cassette	bowl		x				
12	System exhaust					x				
14	System leak?					x				
19	Door opened? - Transfer stopped					х				
21	Chemical Cabinet Leak/Exhaust Fail?		x	x	x					
23	Chemical Cabinet Power Off?		х	x	х					

#### **Dealing with Alarms**

				CHEMIC	CAL CABINE	T (ACMS)					
			State								
Code	Message	Not allow to start new lot	Not send any more wafers from cassette	Not accept next wafer	Stop processing wafer in current process		Audible alarm	Red light	Yellow light	Yellow light flashing	
	Leak detected?		х	х	х		Х	х			
	Exhaust low?		х		х		х	х			
	Bubble detected?		х	х			х	х			
	Canister pressure low?		х	х	x		х	х			
	Pump pressure low?		х	х	х		х	х			
	Canister level high high?		х	x	х		х	х			
	Canister level high?						х		х		
	Canister level low?	x					Х	х			
	Canister level low low?		х				х	х			
	Bottle low level?	х					х		х		
	Controller is off-line?		x	x	х		Х	x			

# Module-Specific Controls

In addition to system-wide tools, the P9000 also provides module-specific tools which enable you to manage the operation of individual modules. These tools become available only when you click/select a module. Refer to Figure 2-1.

# CHAPTER 3 Configuring Programs & Recipes

# Chapter Outline

This chapter discusses the procedures for creating and managing recipes as well as arm, pump, and module programs. It covers the following topics:

- Recipes and programs
- Accessing the Recipes page
- General recipe-creation procedures
- Creating and managing arm programs
- Creating and managing pump programs
- Creating and managing module programs
- Creating and managing recipes
- Sharing programs and recipes
- Managing module settings

# **Recipes and Programs**

Recipes are formulas that the system uses to process wafers. It specifies the system modules to be used for a wafer-processing operation and the sequence in which wafers pass through the modules. Programs, on the other hand, are operational procedures or actions performed by various system components, which include wafer-processing modules (e.g., coaters, etc.), the pumps, and the transfer arms.

#### Note:

Before creating all programs for the components used in the recipe must be created. You CANNOT CREATE A RECIPE WITHOUT THE NEEDED ARM, PUMP, AND MODULE PRO-GRAMS.

# Accessing the Recipes Page

You can create and manage recipes and programs on the Recipes page. To access the Recipes page, click **Recipes** on the navigation bar. Figure 3-1 shows the default Recipes page.

	Connected Count: 7	09/22/2012 5:12:00 PM	@smartPro	P9000	Name: CDAdmin Role: Super User Logon: 0000:01:42:29	🤤 Maintenanc
Programs & Recipes	Module Options					
Recipes Programe Programe Am Prog	Rospe name		Adhor	Reoperane		
	mport Backup	Sharing	(Right click or F2 to rename)	New		Edit Delete



As shown in Figure 3-1, the Recipes page has two tabs across its top: Programs & Recipes and Module Options. The former allows you to create and manage programs and recipes; the latter allows you to choose the system modules and modify their settings. Table 3-1 briefly describes the UI components on the Recipes page.

Tab	Description
Programs & Recipes	The Programs & Recipes tab has four menu options:
	• Recipes — Allows you to create, edit, delete, import, export, and share recipes.
	• Programs — Allows you to create, edit, delete, import, export, and share module programs.
	• Pumps — Allows you to create, edit, delete, import, export, and share pump programs.
	<ul> <li>Arm Programs — Allows you to create, edit, delete, import, export, and share arm programs.</li> </ul>
Module Options	Allows you select or deselect the system modules as well as modify their values.

TABLE 3-1: Recipe Screen UI Components

## General Procedures for Recipe Creation

A recipe encompasses programs which are the operations or events carried out by various system modules during a wafer-processing operation. Recipe creation should follow these general procedures:

- 1. Creating arm programs
- 2. Creating pump programs
- 3. Creating module programs
- 4. Creating recipes

# Managing Arm Programs

Arm programs are an important ingredient of a recipe. This section discusses how to create, edit, delete, import, export, and share arm programs.

Keep in mind that parameters for arm programs differ, depending on the module with which the arm program is associated. The following paragraphs provide general instructions for managing arm programs.

#### **Creating a New Arm Program**

Arm programs govern the operation of the dispense arms. They are important ingredients of recipes. As a best practice, we recommend that you have some arm programs configured before you go about creating a recipe.

To create an arm program:

- 1. On the Recipes page, make sure that the Programs & Recipes tab is selected.
- 2. From the side menu, click the Arm Program tab, as shown in Figure 3-2.

	Connected Count: 985	10/02/2012 5:35:45 PM	@smartP	ro <b>P</b> 90	000	Logon: 0000:07:35	min Joer 1:57	🤤 Syste	em Idle
🛉 Programs & Recipe	1 🏇 Module Options								
	Audiary program name		Туре	Author	- 1	to Audiary operation	Time (p)	Gap (mm)	Pos (T/8
👾 Recipes			* 🕾 Coster		12	Traverse Traverse	0.0 5.0	20.0	8
Programs	BIG_TEBR_70		• 🖘 Coater	CDAdmin	3	Traverse	0.0	20.0	8
	Center		* 🖘 Coater	CDAdmin					
Pumps	🕅 man		-= Coater	CDAdmin					
T Am Prog	💟 man home		• 🖘 Coater	CDAdmin	E				
	V mantop		• 🗢 Coater	CDAdmin					
	V TEST		* 📼 Coater	CDAdmin					
	V TEST-M5000		• 🗢 Coster	CDAdmin					
	DEV_11MM		🗢 Dev	CDAdmin					
	DEV_CENTER		* 👄 Dev	CDAdmin					
	TTO TEET DEV		- n	Chidala	•	<i>(1)</i>	~		
	Import Backup	Sharing	(Right cik	sk or F2 to rena	ите)	New	Edit		Delete

FIGURE 3-2: The arm programs page

3. Click **NEW**. The Create New Program dialog box opens. See Figure 3-3.

Select a kir	nd of mod
	0
Coater	Dev

FIGURE 3-3: Selecting a module

#### Note:

As shown in Figure 3-3, arm programs are needed for Coaters and Developers.

4. Click the desired module. The Arm Program dialog box opens. See Figure 3-4.

Arm Program				
Program name:			<b>A</b>	pproved
Operations	No	Operation Time (s)	Gap (mm)	Pos (T/B)
Traverse				
Sweep				
Home				
		Seve As		
		Save As Save		use

FIGURE 3-4: Creating a new arm program

5. Where it says Program Name, enter a unique name for the arm program.

**6.** Under Operations, highlight a desired option and add it to the right pane by clicking the right arrow. Repeat this step to add the other operations as needed. See Figure 3-5.

Operations	No	Operation	Time (s)	Gap (mm)	Pos (T/E
Traverse		Traverse	0.0	0.0	
Sweep	2	Sweep	0.0	0.0	В
Home	3	Home	0.0	0.0	в



- 7. Highlight each operation and specify the values for Time, Gap, and Position.
- 8. In the upper-right corner of the page, check the **Approved** check box to make it available for use.
- 9. Click Save.

#### Note:

Unless approved, an arm program will not show up on the Arm Program page and, therefore, will not be available for use.

#### **Dispense Arm Operations and Measurement**

The operations of the dispense arms refer to the way they handle wafers. You must specify movement of the dispense arms. Table 3-2 describes the actions the dispense arms can take during a wafer-processing operation.

Dispense Arm Movement	Description
TRAVERSE	The dispense arm moves from the start position to the
	destination position as programmed.
SWEEP	The dispense arm moves back and forth according to the pre-programmed settings.
HOME	The dispense arm returns to its home position above the outer part of the pre-dispense cavity.

TABLE 3-2: Dispense Arm Operation Options

Table 3-3 describes the units of measurement by which the movement of the dispense arm is measured.

Parameter	Description
Time (s)	The time (in seconds) it takes for the dispense arm to complete an event.
	Range: 0 ~ 99.9 seconds.
Gap (mm)	The distance (in millimeters) the dispense arm moves to
	complete an event.
	Range: It varies, depending on the measurement selected in the configuration setting.
Position	The position of the dispense arm.
	Options: T/B (T = top; B = bottom)

TABLE 3-3: Dispense Arm Movement Parameters

The dispense arm can be positioned to start or stop at any wafer radius and in either direction. Each dispense nozzle is automatically referenced to the center of a wafer. When in a processing position, the dispense arm moves at the maximum speed from its HOME position above the pre-dispense cavity to the wafer center line.

#### Modifying an Existing Arm Program

You can modify existing arm programs to accommodate your changing production requirements.

To modify an existing arm program:

- 1. On the Recipes page, make sure the Programs & Recipes is selected.
- 2. From the side menu, click the Arm Prog tab. The Recipes page refreshes.
- 3. From the list of arm programs, highlight the arm program of interest and click **Edit** (or inside the right pane). The Edit Arm Programs dialog box opens.
- 4. Make the desired changes.
- Click Save to save the changes without changing the arm program name or Save As to save the arm program under a different name.

#### Note:

You can also right-click an arm program to bring up the pop-up menu, which allows you to rename, edit, delete, or make a copy of the arm program. See Figure 3-6.



FIGURE 3-6: Arm Programs page pop-up menu
# **Deleting an Existing Arm Program**

The Arm Programs page can become crowded as more arm programs are created. To keep the page less cluttered, you should delete arm programs that are no longer needed.

To delete an arm program:

- 1. On the Arm Programs page, highlight the arm program of interest and click **Delete**.
- 2. When the confirmation message pops up, click Yes.

# **Exporting Arm Programs**

You can export arm programs to a location on your computer, network, or a storage device to back them up.

To export arm programs:

Exp	ort Arm Programs						ingen B			• X
Ð	port path: F:\arm program									Browse
No	Auxiliary program name	Туре	Action	Author	-	No	Auxiliary operation	Time (s)	Gap (mm)	Pos (T/B)
1	BIG_TEBR_6_20	📾 Coater	New	CDAdmin		1	Traverse	0.0	20.0	В
2		- Carlas	New	CDAdata		2	Traverse	5.0	6.0	В
2	BIG_TEBR_/U	Coater	New	CDAdmin		3	Traverse	0.0	20.0	В
3	center	Coater 🦈	New	CDAdmin						
4	doc-1	🗢 Coater	New	CDAdmin						
5	doc-3	Coater 🥌	New	CDAdmin						
6	doc-3 - Copy	Coater 🥌	New	CDAdmin	н					
7	man	Coater 🦈	New	CDAdmin						
8	man home	Coater 🥗	New	CDAdmin						
9	mantop	Coater 🥗	New	CDAdmin						
10	TEST	Coater 🥗	New	CDAdmin						
11	TEST-M5000	Coater 🥗	New	CDAdmin	Ц					
12	DEV_11MM	🗢 Dev	New	CDAdmin						
13	DEV_CENTER	🗢 Dev	New	CDAdmin	-					
	Select All							Export	C	ose

1. On the Arm Programs page, click **Backup**. The Export Arm Programs dialog box opens. See Figure 3-7.



- 2. Click **Browse** and select the export path.
- 3. Check the Select All check box and click Export.
- 4. When the confirmation message shows up, click **OK**.
- 5. Click **Close** to exit the Export Arm Programs page.

## **Importing Arm Programs**

If you have arm programs saved on your system, network, or a storage device, you can easily import them to the system's database.

To import arm programs:

1. On the Arm Programs page, click **Import**. The Import Arm Program dialog box opens. See Figure 3-8.

Imp	port Arm Programs						Lugar and	1.00		• ×
Im	port path: C:\SmartPro P9000\Arm	nPrograms								Browse
No	File name	Туре	Action	Author	Date	No	Auxiliary operation	Time (s)	Gap (mm)	Pos (T/B)
1	BIG_TEBR_6_20	🕿 Coater			09/22/12	1	Traverse	0.0	20.0	В
2	BIG_TEBR_70	🗢 Coater	Override	CDAdmin	09/21/12	2	Traverse Traverse	5.0 0.0	6.0 20.0	B
3	center	Coater 🥌	Override	CDAdmin	09/19/12					
4	DEV_11MM	Dev 🗇	Override	CDAdmin	09/22/12					
5	DEV_CENTER	🗢 Dev	Override	CDAdmin	09/21/12					
6	man home	Coater (	Override	CDAdmin	09/24/12					
7	man	Coater (	Override	CDAdmin	09/24/12					
8	mantop	Coater 🥌	Override	CDAdmin	09/24/12					
9	TEST	🗢 Coater	Ovemide	CDAdmin	09/22/12					
10	TEST_DEV	Dev	Override	CDAdmin	09/19/12					
11	TEST_DV_TRAVERSE	S Dev	Override	CDAdmin	09/19/12					
	Select All				Delete File			Import	С	ose

FIGURE 3-8: Importing arm programs

- 2. Click Browse. The Browse For Folder dialog box opens.
- 3. Browse for the folder containing the arm programs and click **OK**.
- 4. In the Import Arm Programs dialog box, check the Select All check box, and click **Import**.
- 5. When the confirmation message shows up, click **OK**.

6. Click **Close** to exit the Import Arm Programs page.

#### Note:

If you do not want to import an arm program, you can highlight it and click **Delete File** before you click **Import**.

#### **Sharing Arm Programs**

Normally, arm programs created by a user may not be available for use by other users unless they are shared. Sharing arm programs means placing them in the Public pane on the Arm Programs page so that other designated users can access them.

To share arm programs:

1. On the Arm Programs page, click **Share.** The Arm Programs Sharing dialog box opens. See Figure 3-9.

TÍN	ate (Double click, right click o	r F2 to rename)					De	tails			
DAd	min					•	No	Auxiliary operation	Time (s)	Gap (mm)	Pos (T/B
lo	Arm program name		Туре	Author	Shared	-	1	Home	0.0	1.0	В
	BIG_TEBR_6_20	- ,	Coater	CDAdmin	V	=	2	Sweep	2.0	1.0	В
	BIG_TEBR_70		🗢 Coater	CDAdmin	1		3	Traverse	1.0	2.0	В
	center		🗢 Coater	CDAdmin	1						
	doc-1		🗢 Coater	CDAdmin	V						
	doc-3		🕿 Coater	CDAdmin	<b>V</b>						
	doc-3 - Copy		🗢 Coater	CDAdmin		-					
ut		▲ Import			📑 Del	ete					
lo	Arm program name		Туре	Author	Modified						
	BIG_TEBR_6_20		🗢 Coater	CDAdmin	09/24/20	12					
	BIG_TEBR_70		🖘 Coater	CDAdmin	10/02/20	12					
	center		🗢 Coater	CDAdmin	09/24/20	12					
	doc-1		🗢 Coater	CDAdmin	10/02/20	12					
	doc-3		🗢 Coater	CDAdmin	10/02/20	12					

FIGURE 3-9: Sharing arm programs

- 2. In the Private pane, click the down arrow and select a user account whose arm programs you want to share, and check the arm programs to be shared. The arm programs will be added to the Public pane below as you check them.
- **3.** In the Public pane, click the down arrow to select the user with whom the arm programs will be shared.
- 4. Click **Close** when done.

# Managing Pump Programs

Like arm programs, pump programs are also an important part of a recipe. This section discusses how to create, modify, delete, import, export, and share pump programs.

# **Creating a New Pump Program**

You can create a new pump program using the following procedures:

- 1. On the Recipes page, make sure that the Programs & Recipes tab is selected.
- 2. From the side menu, click Pumps. The Recipes page refreshes.
- **3.** On the Pumps page, click **New**. The Create New Pump Program dialog box opens. See Figure 3-10.

C & D	Count: 985	10/02/2012 6:31:55 PM	©smart	Pro P9	000	Name: CDAdmin Role: Super User on: 0000:08:36:07	🤤 System Id
Programs & Recipe	s 🎲 Module Options						
	Pump program nam		Туре	Author	Field	Value	
Recipes	COAT1A		M300	CDAdmin	Program Name Pump Type	COATIA M300	
Programs	COAT1C		- M300	CDAdmin	Delay Time Enabled Delay Time	N 1.20 sec	
	COAT2A	Creat	a New Dumo Program		Dispense Time	5.00 sec 15 psi	
Vumps	COAT2C		Select a kir	nd of pump		Yes CDAdmin 9/25/2012 7:49:4	15 PM
* Arm Prog	M5000-DEFAULT					Yes	
	M5000-PUMP1		M300	M5000S			

**4.** Select a pump type. The Pump Program Builder dialog box opens. See Figure 3-11.

riogrammanic.	doc-1				Approved
Pump type:	M300	) -	Pumpo	output:	Output 1 🔹
Filed Name			Value	Unit	Range
Delay Time Enal	oled		Y		N = No; Y = Yes
Delay Time			1.20	sec	1.20 sec -> 60.00 sec
Dispense Time			0.00	SAC	0.00 sec -> 100.00 sec
Dispense Pressu	re		6	Edit	F2 5 psi

FIGURE 3-11: The Pump Program Builder dialog box

- 5. Where it says Program Name, enter a unique name for the pump program.
- **6.** Where it says Pump Output, click the down arrow and select an option from the drop-down menu.
- 7. In the Value column, highlight a field and enter a desired value. Repeat this step to specify the other values as needed.
- 8. Click Save.

# Modifying an Existing Pump Program

You may need to modify the configuration of existing pump programs to accommodate changes in your production requirements.

To modify an existing pump program:

- 1. On the Recipes page, make sure the Programs & Recipes tab is selected.
- 2. From the side menu, click the Pumps tab. The Recipes page refreshes.
- **3.** On the Pumps page, highlight the pump program of interest and click **Edit.** The Edit Pump Program dialog box opens.
- 4. Make the desired changes.
- Click Save to save the changes without changing the program name or Save As to save the program under a different name.

#### Note:

You can also right-click the pump program to bring up the pop-up menu, which provides options for you to rename, edit, delete, or make a copy of the pump program. See Figure 3-12.

C & D	Connected Count: 985	10/02/2012 6:43:46 PM	©smarti	Pro P9	Logon: 0	lame: CDAdmin Iole: Super User 000:08:47:58	🤤 System Idle
Programs & Recipe	es 🎥 Module Options						
	Pump program name		Туре	Author	Field	Value	
A Recipes	COAT1A		M300	CDAdmin	Program Name Pump Type	COAT2C M300	
Programs	COAT1C		• M300	CDAdmin	Delay Time Enabled Delay Time	2 N 1.20 sec	
	COAT2A		M300	CDAdmin	Dispense Time Dispense Pressure Approved	5.00 sec 15 psi Yes	
🚺 Pumps	COAT2C				Modified User	CDAdmin	
P. Ann Press	doc-1		Rename	9	F2	~^25/2012 7:50:13 =s	PM
Amirrog	M5000-DEFAULT		Edit		Enter		
	M5000-PUMP1		Make a	CODV	Ctrl+LeftClick	_	
	Bakin	Shring	(Right click o	r F2 to rename)	Ner		Fe Delete

FIGURE 3-12: Pumps page pop-up menu

# **Deleting a Pump Program**

You can delete pump programs that are no longer needed.

To delete a pump program:

- 1. On the Recipes page, make sure that the Programs & Recipes tab is selected.
- 2. From side menu, click the Pumps tab. The Recipes page refreshes.
- 3. On the Pumps page, highlight the pump program of interest and click **Delete**.
- 4. When the confirmation message shows up, click **Yes.**

# **Exporting Pump Programs**

You can export pump programs to back them up on your computer, network, or storage device outside the system's database.

To export pump programs:

- 1. On the Recipes page, make sure that the Programs & Recipes tab is selected.
- 2. From the side menu, click the Pumps tab. The Recipes page refreshes.
- **3.** On the Pumps page, click **Backup**. The Export Pump Programs dialog box opens. See Figure 3-13.





- 4. Click **Browse.** The Browse For Folder dialog box opens.
- 5. Browse for the location where the pump programs are to be saved and click OK.
- 6. In the Export Pump Programs dialog box, check the Select All check box.
- 7. Click Export.
- 8. When confirmation message shows up, click OK.
- 9. Click Close.

## **Importing Pump Programs**

If you have pump programs saved on your system, network, or storage device, you can import them to the system's database.

To import pump programs:

- 1. On the Recipes page, make sure that the Programs & Recipes tab is selected.
- 2. From the side menu, click the Pumps tab. The Recipes page refreshes.
- **3.** On the Pumps page, click **Import**. The Import Pump Programs dialog box opens. See Figure 3-14.





- 4. Click **Browse** to browse for folder that contains the pump program files.
- 5. In the Import Pump Programs dialog box, check the **Select All** check box.
- 6. Click **Import**.
- 7. When the confirmation message pops up, click OK.

#### Note:

If you want to exclude some of the pump program files from being imported, you can do so by highlighting them, one by one, and then clicking **Delete File** before clicking **Import**.

#### Sharing Pump Programs

Normally, pump programs created by a user won't be available for use by other users unless they are shared. Sharing pump programs means placing them in a public area on the Pump Programs page so that other users of the system can access and use them.

To share pump programs:

- 1. On the Recipes page, make sure that the Programs & Recipes tab is selected.
- 2. From the side menu, click the Pumps tab. The Recipes page refreshes.
- **3.** On the Pumps page, click **Share.** The Share Pump Programs dialog box opens. See Figure 3-15.

riv	(Double click, right click or F2 to rename)					Details	
DAd	lmin				-	Field	Value
No	Pump program name	Туре	Author	Shared	•	Program Name	COAT1A
	COATIA	M300	CDAdmin	7		Pump Type Output	M300
	COATIC .	M300	CDAdmin			Delay Time Enabled	N 1.20 sec
	COAT2A	M300	CDAdmin		E	Dispense Time	29.00 sec
	COAT2C	M300	CDAdmin			Approved Modfind Liner	Yes
5	doc-1	M300	CDAdmin			Modified Date	10/2/2012 6:49:24 PM
	M5000-DEFAULT	M5000S	CDAdmin		-	Sharing	No
Pul	Dlic Import			🙀 Del	ete		
all us	ers)				•		
No	Pump program name	Туре	Author	Modified			
	COAT1C	M300	CDAdmin	10/02/20	12		
	COAT1A	M300	CDAdmin	10/02/20	12		

- 4. In the Private pane, click the down arrow and select a user account whose arm programs you want to share, and check the pump programs to be shared. The programs will be added to the Public pane below as you check them.
- **5.** In the Public pane, click the down arrow to select the user account with whom the pump programs are to be shared.
- 6. Click Close.

# Managing Module Programs

Module programs are programs configured for system modules that are used in a wafer-processing operation, such as coaters, chill plates, hot plate ovens, etc. To ensure that all system modules operate in the way you want them to, you must have them properly programmed.

# **Creating a New Module Program**

You must configure programs for all the system modules before creating recipes.

To create a module program:

1. On the Recipes page, make sure that the Programs & Recipes tab is selected.

- - X SmartPro P9000 - Build 2012.10.3 - 11.56 (CoreMultiWafer2\_1) Name: CDAdmin Connected 10/08/2012 Maintenance 2 CBD @smartPro P9000 Role: Super User Count: 1028 5:43:40 PM Logon: 0000:00:40:49 SERVICES, INC. 🔶 Programs & Recipes 🌸 Module Options Program name Туре Author No Operation Delay In Chill Time Cool 0.0 0.0 Recipes Chil\_Test • Chill CDAdmin Hoo Empty Hpo CDAdmin ٢ Hpo\_Test • 👄 Hpo CDAdmin Coater\_Empty \* 🗢 Coater CDAdmin Arm Prog Coater\_Test • 🖘 Coater CDAdmin (Right click or F2 to rename) Import Backup Sharing New Edit Delete 0 Alarms • Help Main Datalog Silence System Setup 0
- **2.** From the side menu, click the Programs tab. The Recipes page refreshes. See Figure 3-16.

FIGURE 3-16: Creating a new module program

3. Click New. The Select a module dialog box opens. See Figure 3-17.



#### FIGURE 3-17: Selecting a module

Coater	Auxiliary Am Programs:
New event	No Auxiliary am program name
Spin Tee FPP	1 Am 1
Bottom EBR	2 Am 2
Dispense 1	
Dispense 2	3 Am 3
Dispense 3	4 Am1
Dispense 4	
Dispense 5	5 center
Oscillate	6 tebr-2in
Oscillate - Disp1	7 446-26 0000
Oscillate - Disp2	New Arm Edit Arm Delete Arm
Oscillate - Disp3	
Oscillate - Disp5	No Auxiliary operation Time (s) Gap (mm) Pos (T/
oscinute onpo	1 Traverse 1.1 2.2 B

**4.** Click a module. (For illustration purposes, we select Coater.) The Coater Program Builder dialog box opens. See Figure 3-18.

FIGURE 3-18: Creating a new coater program

- 5. Enter a unique name for the program.
- 6. Click **New Event** and select the events from the drop-down list menu. The selected events show up on the screen. See Figure 3-19.

2	Coater						Ranges: 0.0 s -> 999.9 s	Auxilia	ary Arm Programs:			
	Operation	Time	Spd. rpm	Acc krpm	Ocs. ms	Exh klpm	Arm program	No	Auxiliary arm program name			
1	Spin	10.0	0	50		0	8		New Arriston			
2	Top EBR	20.0	0	50		0	×	1				
3	Bottom EBR	I	0	50		0	*	2	1-2			
\$	Dispense 1	0.0	0	50		0	×	2	Arm 2			
5	Dispense 2	0.0	0	50		0	×	2	Arm 2			
1	Oscillate	0.0	0		90	0	*	5	74111.5			
1	Oscillate - Disp1	0.0	0		90	0	*	4	Arm 1			
3	Oscillate - Disp2	0.0	0		90	0	×					
									New Arm Edit Arm		De	sete Arm
								No	Auxiliary operation	Time (s)	Gap (mm)	Pos (T/E
								1	Traverse	1.1	2.2	В

FIGURE 3-19: Configuring Coater events

- **7.** Specifying the parameters of each event by highlighting the values and override them with desired ones.
- 8. Click Save.
- 9. When the confirmation message shows up, click **OK**.
- 10. Click **Close** to exit the Program Builder dialog box.

#### Note:

If for some reason you want to remove an event from the Coater Program Builder, simply click the corresponding letter X and then the letter D, as shown in Figure 3-20. The event will be removed when the page refreshes.

ogran	m name:											V	Approve
•	Coater	Time	Sed	Acc	0.0	Exh			Auxilia	ry Arm Programs:			
	Operation	S	rpm.	krpm	ms	klpm	Arm program		No	Auxiliary arm program name			
1	Spin	10.0	0	50		0		*	1	Am 1			
2	Top EBR	20.0	0	50		0			· ·	AULT			
3	Bottom EBR	0.0	0	50		0		*	2	Arm 2			
4	Dispense 1	0.0	0	50		0		<b>X</b>					
5	Dispense 2	0.0	0	50		0		*	3	Arm 3			
5	Oscillate Diret	0.0	0		90	0							_
-	Oscillate - Disp1	0.0	0		30	0			4	Arm 1			
									-	tabe on Lanu			
									No	Auxiliary operation	Time (e)	De	lete Arm
									No 1	Auxiliary operation Traverse	Time (s)	De Gap (mm) 2.2	lete Arm Pos (T/B B

FIGURE 3-20: Deleting an event from the Coater Program Builder

# **Editing Existing Module Programs**

You have to edit your existing module programs to accommodate changes in your production requirements.

To edit an existing module program:

- 1. On the Recipes page, make sure that the Programs & Recipes tab is selected.
- 2. From the side menu, click Programs. The Recipes page refreshes.
- **3.** On the Programs page, highlight the program of interest and click **Edit.** The Edit Program dialog box opens.
- 4. Make the desired changes.
- Click Save to save the changes without changing the program name, or Save As to save the program under a different name.
- 6. Click **Close**.

# **Deleting Module Programs**

You can delete module programs that are no longer needed.

To delete a module program:

- 1. On the Programs page, highlight the program of interest.
- 2. Click Delete.
- 3. When the confirmation message shows up, click Yes.

## **Exporting Module Programs**

You can export modules programs so that you can back them up on your hard drive, network, or removable storage device.

To export your module programs:

 On the Programs page, click **Backup.** The Export Programs dialog box opens. See Figure 3-21.

Export Programs						- 0 - X
Export path	n: C:\Users\CD\Desktop\P9	000 screen	ishots\B/	ACKUP		Reawse
No Program nam 1 Chil_Empty 2 Chil_Test 3 Hoo_Empty 4 Hoo_Test 5 Coster_Empty	ие	Type Chill Chill Hipo Hipo Coster	Action New New New New	Author CDAdmin CDAdmin CDAdmin CDAdmin CDAdmin		
6 Coater_Test 7 doc-1		Coater	New New	CDAdmin CDAdmin		
Select A	JI				Export	Close



- 2. Click **Browse**. The Browse For Folder dialog box opens.
- 3. Browse for the location where the programs files are to be saved and click OK.

- 4. In the Export Programs dialog box, check the **Select All** check box.
- 5. Click Export.
- 6. When the confirmation message shows up, click **OK**.
- 7. Click **Close**.

#### Note:

You can remove programs from the list of programs to be imported by highlighting them, one at a time, and clicking **Delete File.** See Figure 3-22.

Sm	artPro P9000 - B	Connected	10/08	/2012	^	12		20000	6		Name: CDAdmir	1	Main	tono	
Inc	CED	- 1000	0.00.0	12012	<u>()</u> SП	nartp	0	P9000		2	Role: Super Use	er	e Main	itenar	nc
Imp	ort Programs									-	-	-			_
In	port path:	C:\Users\CD\Des	ctop\P900	0 screen:	shots\BA(	CKUP								Browse	•
No	File name		Туре	Action	Author	Date	No	Operation	Time	Gap	Temperature	Band			
	Chill_Empty		Chill	Override	CDAdmin	10/04/12	1	Step Step	0.0 30.0	5.0 5.0	25.00 25.00	500.00 500.00			
	Chill_Test		Chill	Override	CDAdmin	10/03/12									
	Coater_Empty		Coater 🍮	Override	CDAdmin	10/04/12									
	Coater_Test		Coater	Override	CDAdmin	10/04/12								_	_
	doc-1		Coater (	Override	CDAdmin	10/08/12	Sma	artPro P9000						2	3
	Hpo_Empty		👄 Нро	Override	CDAdmin	10/04/12		Are you s	ure you	want t	o delete file "C	:\Users\CD	\Desktop\P9	000	
	Hpo_Test		👄 Нро	Ovenide	CDAdmin	10/03/12		screensh	ots\BACI	KUP\H	po_Test.Hpo.p	prog"?			
											6	Yes		No	
							L			_					
													2		
	Select All					Delete File						Import		Close	



## **Importing Module Programs**

If you have module programs saved on your computer, network, or storage device, you can import them to the system's database.

To import module programs:

- 1. On the Programs page, click **Import.** The Import Programs dialog box opens.
- 2. Click **Browse.** The Browse For Folder dialog box opens.

- 3. Browse for the location where the programs files are located and click OK.
- 4. In the Import Programs dialog box, check the **Select All** check box.
- 5. Click Import.
- 6. When the confirmation message pops up, click OK.

#### **Sharing Module Programs**

Typically, module programs created by a user won't be available for use by other users unless they are shared. Sharing module programs means placing them in a Public pane on the Programs page so that other users of the system can access and use them.

 On the Programs page, click Share. The Program Sharing dialog box opens. See Figure 3-23.

			•	No Operation	Delay In	Chill Time	
Type	Author	Shared		1 Cool	0.0	0.0	
⇔ Chil	CDAdmin						
* 👄 Chill	CDAdmin						
🥌 Hpo	CDAdmin		=				
• 👄 Hpo	CDAdmin						
• 📼 Coater	CDAdmin						
* 🖘 Coater	CDAdmin		-				
Import		in De	-				
Туре	Author	Modified					
	Type Coll Hoo Coll Coster Coster Coster Type	Type Author COArrin CoArrin CoArrin Phos CDArrin Phos CDArrin Phos CDArrin Coater CDArrin Coater CDArrin Coater CDArrin Type Author	Type Author Shared	Type Author Shared  Type Author Shared  Coldmin  Coldmin  Pipo CDAdmin  Pipo CDAdmin  Coldmin  Coldmin  Coldmin  Coldmin  Coldmin  Coldmin  Type Author Modified  Type Author Modified	No Operation     Type Author Shared     Coll CDAdmin     Pipo CDAdmin     Pipo CDAdmin     Coster CDAdmin     Coster CDAdmin     Coster CDAdmin     Type Author Modified	Type     Author     Shared       Coll     CDAdmin       Hoo     CDAdmin       Hoo     CDAdmin       Hoo     CDAdmin       Coll     Coll	Type     Author     Shared       Cod     0.0     0.0



- 2. In the Private pane, click the down arrow and select a user account whose arm programs you want to share, and check the module programs to be shared. The programs will be added to the Public pane below as you check them.
- **3.** In the Public pane, click the down arrow to select the user account with whom the module programs are to be shared.

# 4. Click Close.

# Managing Recipes

A recipe can contain one or more flows, each representing a system module, e.g., Coater, Chill, Alloy, Vapor Prime, and Centering. When creating a recipe, you must first select a flow and then add events to the flow. Events are actions performed by a system module. Events are module-specific, meaning different modules may or may not have the same events. Once you have added events to a flow, the next thing you do is to add arm and pump programs to it.

To help make recipe creation easier, we recommend that you create arm, pump, and module programs first. With all programs in place, you can simply add them to the recipe you are creating.

# **Creating New Recipes**

The most efficient way to operate the P9000 is through the use of recipes, which is a series of modules arranged in a certain sequence. Before you start creating a recipe, make sure that you have programs in place for all the system modules, pumps, and dispense arms.

To create a new recipe:

1. On the Recipes page, make sure that the Programs & Recipes tab is selected.



2. From the side menu, click Recipes. The Recipes page opens. See Figure 3-24.

FIGURE 3-24: Managing recipes



**3.** On the Recipes page, click **New**. The Recipe Builder page opens. See Figure 3-25.

FIGURE 3-25: Creating a new recipe

- 4. Where it says Recipe Name, enter a unique name for the recipe.
- 5. In the Click **New** and create a work flow by selecting the desired modules from the list menu. See Figure 3-26.



FIGURE 3-26: Creating a work flow

**6.** After you have selected all the modules for the work flow, click the down arrow next to each module and select the components to be used in the work flow. See Figure 3-27.



FIGURE 3-27: Selecting system modules

- **7.** To add a program to a module, highlight the module, and click the Programs tab on the right to select a program for the module.
- **8.** To add a pump program to the module, click the Pumps tab on the right and select a pump program.
- **9.** Repeat Steps 7 through 8 to add module and pump programs to the other modules in the work flow.
- **10.** Make sure to check the Approved check box in the upper-right corner of the page.
- **11.** Click **Save** when completed. The new recipe will be added to the collection of recipes on your system and ready to use.

## Modifying an Existing Recipe

You can modify an existing recipe to accommodate for changes in your production requirements. After you have made the needed changes, you can either save the

changes without changing the name of the recipe or save the recipe under a different name.

Also, if you are unfamiliar with the recipe concept used in the P9000 Cluster System, agood way to get started is by opening an existing recipe and see what it consists of. You can then try to modify the parameters to see how they work.

To modify an existing recipe:

- 1. On the Recipes page, make sure the Programs & Recipes tab is selected.
- From the side menu, click Recipes. The Recipes page opens, showing all available recipes. See Figure 3-28.

o C&D SmartPro P900	00 - Version 2.1.1742.93 (iCore.Multiwafers -	New Algorithm)	
<b>C &amp; D</b>	Disconnected         11/07/2013           Count: 0         9:46:11 AM	smartPro P9000	Name: Admin Role: Administrator
SERVICES. INC.	S PLEASE RESET SYSTEM TO	) INITIALIZE	Iranster Stop
👷 Programs & Recipes	nodule Options		
	Recipe name A	Author DEMO2	Any size <u>Hide all</u>
😭 Recipes	DEMO A	dmin 1 Mech. Center	ing
Programs	U DEMO2 A	dmn         Coster 1, Cost           Coster (45s)         No. Operation           1         Dispense 1 (D' 2 Spin           3         Dispense 5 (D2           4         Dispense 5 (D2           4         Dispense 5 (D2           3         HPO 150 degree           No. Operation         1           Bake         No. Operation	Edit         Hide           Time         Spd.         Acc         Ocs         Exh         Arm program           0         0.0         0.50.0         0         home         0           50.0         0.0         50.0         0         home         0           9)         0.0         0         50.0         0         home         0           Hpo3. Hpo4         Edit            Time         Gap         Temperature         Band         Hide           60.0         150.00         400.00         150.0
	► Import €xport Sharing	4 New	Edit Hide Delay In Chill Time Vacuum On 0.0 12.0 Yes Edit Yes
Main	System Crecipes	Datalog Setup	Alarms 💋 Silence 😲 Help

FIGURE 3-28: Selecting a recipe to edit

**3.** Highlight the recipe of interest and click **Edit**. The Recipe Builder dialog box opens, showing the flow of the recipe. See Figure 3-29.



FIGURE 3-29: Editing a module program

- 4. Highlight a module of the recipe.
- **5.** To change the program of the module, click the Programs tab and make the desired changes to the program by highlighting the values and overriding them with new ones.
- **6.** To change the pump program, click the Pumps tab and make the desired changes to the pump program by highlighting the values and overriding them with new ones.
- 7. Click **Save** to save the changes without renaming the recipe or **Save As** to save it as a different recipe.
- **8.** Optionally, you can also add new modules to the recipe flow by using the New button, as described in the previous section.

# **Deleting an Existing Recipe**

As more recipes are created, the recipe screen can become cluttered, making recipe selection less convenient. To solve this issue, you may need to delete recipes that you no longer need.

To delete a recipe:

- 1. On the Recipes page, make sure the Programs & Recipes tab is selected.
- 2. From the side menu, click Recipes. The Recipes page opens. See Figure 3-30.



FIGURE 3-30: Deleting a recipe

- 3. Highlight the recipe of interest and click Delete.
- 4. When the confirmation message appears, click **Yes**.

# **Exporting Recipes**

You can export recipes out of the system's database so that you can back them up on your hard drive, network, or removable storage device.

To export recipes:

- 1. On the Recipes page, make sure that the Programs & Recipes tab is selected.
- From the side menu, click the Recipes. The Recipes page refreshes. See Figure 3-31.

C&D SmartPro P900	0 - Version 2.1.1742.9 <b>R</b> Disconnected Count: 0	93 (iCore.Multiw 11/07/2013 9:46:11 AM	afers - New Algo	<sup>rithm)</sup> rtPro	P9000		Na Ro	ime: Ad le: Adm 000-01	min iinistrat	or 1	😑 Init	ialize
SERVICES. INC.	🚯 PLEASE R	ESET SYSTE	M TO INITIAL	IZE		Lug	011. 0	000.0			STOP	Stop
Programs & Recipes	Module Options											
	Recipe name		Author	DEMO2							Any size	Hide a
🔶 Recipes	DEMO		Admin	1 📟	Mech. Centering							
A Programs	DEMO2		Admin	2 No. 2 No. 1 2 3 4	Coater1, Coater2 er (45s) Operation Dispense 1 (D1) Spin Dispense 4 (D4) Dispense 5 (D5)	<b>Time</b> 0.0 55.0 0.0 0.0	Spd. 0 200 0	Acc 50.0 50.0 50.0 50.0 50.0	Ocs.	Exh 0 0 0 0	<u>Ec</u> Arm program home	<u>it Hide</u>
👫 Arm Prog				3 HPO No. 1	Hpo1, Hpo2, Hpo 150 degree Operation Bake	<b>3. Hpo4</b> Time 60.0	Gap	Tempe 150.00	rature	Band 400.0	Ec 1 20	<u>iit Hide</u>
				4 No. 1	Chill1, Chill2 chill Operation Cool	Delay Ir 0.0	n Chi 12.0	ll Time )	Vaci Yes	um On	Ec	<u>iit Hide</u>
4	- Import	Sharing		Ner Ner	N					0	Edit	< Delete
Main 4	System	Recipes	Datalog	<b>Q</b>	Setup	<b>I</b> AI	arms		t/s	Sile	nce 🤅	Help

FIGURE 3-31: Exporting recipes

- 3. Click **Export.** The Export Recipes dialog box opens.
- 4. Click **Browse**. The Browse for Folder dialog box opens. See Figure 3-32.





- 5. Browse for the location where you want to back up the recipes and click **OK**. The dialog box closes.
- 6. In the Import Recipes dialog box, check the **Select All** check box and click **Export.**
- 7. When the confirmation message appears, click OK.

## **Importing Recipes**

If you have recipes saved on your computer, network, or a storage device, you can import them to the system's database.

To import recipes:

- 1. On the Recipes page, make sure that the Programs & Recipes tab is selected.
- 2. From the side menu, click Recipes. The Recipes page refreshes.
- 3. On the Recipes page, click **Import**. The Import Recipes dialog box opens.
- 4. Click **Browse**. The Browse For Folder dialog box opens.
- 5. Browse for the recipes and click **OK**.
- 6. In the Import Recipes dialog box, check the **Select All** check box.
- 7. Click Import.
- 8. When the confirmation message pops up, click **OK**.

#### Note:

If you want to exclude some recipes files from being imported, you can do so by highlighting them and clicking **Delete File** before clicking **Import**.

## **Sharing Recipes**

Normally, recipes created by a user may not be available for use by other users unless they are shared. Sharing recipes means placing them in the Public pane on the Recipes page so that other users can access and use them..

To share recipes:

- 1. On the Recipes page, make sure the Programs & Recipes tab is selected.
- From the side menu, click Recipes. The Recipes page refreshes. See Figure 3-33.

	Connected Count: 1028	10/08/2012 6:59:58 PM	@smartPr	0	9000	Logon:	Name: CDAdmin Role: Super User 0000:01:57:07	😑 Maintenance
Programs & Recipes	Module Options							
	Recipe name		Author	Re	cipe name: aaa			
Reopen			CDAdmin	1	Coater 1.0	Coater2		
Programs	V rec		CDAdmin	2	Hpo Test	2. Hpo3. I	tpot	
				3	Chill Test	112		
V Pumps				4	Centering			
Arm Prog					formet			
	Import Backup	Sharing	(Right click or F2 to rename)		New			Edit Delete
Main	System	Recipes	Datalog 6	-	Setup	Alara	. IL Sile	nce 🕢 Help

FIGURE 3-33: Sharing recipes

3. Click Share. The Share Recipes dialog box opens. See Figure 3-34.

Private (Double click, right click or F2 to rename)		Details
DAdmin I usert) Schemen rec rec Public il users)	CDAdmin 🔲	Recipe name: asa          Recipe name: asa         1       Coater 1, Coater 2         Coater Empty         2       Hpo1, Hpo2, Hpo3, Hpo4         4       Chill 1. Chill 2         Chill Test       Contering         Inone       Inone
ko Recipe name	Author Modified	Close



4. In the Private pane, click the down arrow and select a user account whose recipes you want to share, and check the recipes to be shared. The recipes will be added to the Public pane below as you check them. See Figure 3-35.

CDAdmin		•	Recipe name: rec
No Recipe name aaa rec rec Public	Author CDAdmin CDAdmin	Shared	Coater1           Coster_Test           Hpo1           Hpo.Test           Chill           Chill_Test           Source           Chillon           Chillon
(mage)			
all users) No Recipe name	Author	Modified	
all users) No Recipe name 1 aaa	Author CDAdmin	Modfied 10/08/2012	
(all users) No Recipe name 1 aaa 2 rec	Author CDAdmin CDAdmin	Modfied 10/08/2012 10/08/2012	

FIGURE 3-35: Selecting recipes to share

- **5.** In the Public pane, click the down arrow to select the user account with whom the recipes are to be shared.
- 6. Click **Close** when done.

# Managing Module Options

The Recipes page comes with a Module Options tab, which shows the options for the various modules on the P9000, such as Coaters, Developers, Vapor Primer, and Hot Plate Ovens, etc. Options are the operations or events performed by the modules. From the Module Options page, you are able to view the options available for each module and change the values of each option unless it is marked read-only.

# Accessing the Module Options Page

You can access the Module Options page using the following procedures:

1. On the navigation bar, click Recipes. The Recipes page opens.

C & D	TOR	Oisconnected 10/28/2013     Count: 0 2:41:59 PM     O PLEASE RESET SYSTI		E Pro P	9000	Role: Administrator Log On: 0000:01:05:23	Maintenanc     Transfer     Stop
/ Programs & Re	No.	Option name	Min	Max	Value	Unit	*
Coater1	1	Spin speed band	0	9999	77	RPM	Downloa
Conter2	2	Exhaust control on/off	0	1	1	0: Off / 1: On	(approximate)
	3	Idie exhaust value	0	99	77	LPM	G Backup
🌖 Hpo1	4	Pre-dispense delay	0	999	34	Seconds (999: Disable)	Restore
Hen2	5	Post pre dispense delay	0	99	33	Seconds	
	6	Dunker refill interval	0	999	444	Seconds (999. Disable)	
🗢 Hpo3	7	Dunker refill duration	0	9	9	Seconds	
	8	Pump/Canister for dispense 1	0	1	P	0/P = Pump; 1/C = Canister	
Hpo4	9	Pump/Canister for dispense 2	0	1	P	0/P = Pump; 1/C = Canister	
😎 Hpo5	10	Pump/Canister for dispense 3	0	1	с	0/P = Pump, 1/C = Canister	
	11	Pump/Canister for dispense 4	0	1	с	0/P = Pump; 1/C = Cenister	
🈎 Нроб	12	Pump/Canister for dispense 5	0	1	с	0/P = Pump: 1/C = Canister	
	13	Pre-dispense before each new lot	0	1	N	0/N = No; 1/Y = Yes	
	14	Soak nozzles before each new lot	0	1	N	0/N = No: 1/Y = Yes	
	15	Cash analas istantal	1	0000	0000	Canada (0000, Dashia)	*

**2.** From the top of the Recipes page, click the Module Options tab. The Module Options page opens. See Figure 3-36.

FIGURE 3-36: The Module Options page

## Viewing a Module's Options

As you have noticed, the left side of the Module Options page displays all modules available on the P9000. It serves as the menu bar of the Module Options page.

To see the options of a specific module:

1. From the left side of the Module Options page, click the module of interest. The Module Options page refreshes, displaying options available for that module.

# Modifying an Option Value

You can modify the value of any option for a module as long as it is not read-only.

To modify the value of an option:

- 1. On the side menu of the Module Options page, click the module of interest.
- **2.** Identify the option of interest, highlight its value, override it with a new one, and click Save. See Figure 3-37.

C & D MICONDUC	TOR	Image: Disconnected         10/28/2013           Count: 0         2:41:59 PM           Image: Disconnected         2:41:59 PM           Image: Disconnected         2:41:59 PM           Image: Disconnected         2:41:59 PM		t <b>ProP</b>	9000	Name: Admin Role: Administrator Log On: 0000:01:05:23	Stop
Programs & Rec	ipes	Nodule Options					
Coater1	No	Option name	Min	Max	Value	Unit	Downl
	1	Spin speed band	U	3333	11	RPM	
Coater2	2	Exhaust control on/off	0	1	1	0: Off / 1: On	G Back
	3	Idle exhaust value	0	99	77	LPM	
Hpol	4	Pre-dispense delay	0	999	34	Seconds (999: Disable)	Rest
Hpo2	5	Post pre-dispense delay	0	99	33	Seconds	
	6	Dunker refill interval	0	999	444	Seconds (999: Disable)	
▶ НроЗ	7	Dunker refill duration	0	9	9	Seconds	
	8	Pump/Canister for dispense 1	0	1	P	0/P = Pump; 1/C = Canister	
Hpo4	9	Pump/Canister for dispense 2	0	1	Ρ	0/P = Pump; 1/C = Canister	
Hpo5	10	Pump/Canister for dispense 3	0	1	с	0/P = Pump; 1/C = Canister	
	11	Pump/Canister for dispense 4	0	1	С	0/P = Pump; 1/C = Canister	
Hpo6	12	Pump/Canister for dispense 5	0	1	с	0/P = Pump; 1/C = Canister	
	13	Pre-dispense before each new lot	0	1	Ν	0/N = No; 1/Y = Yes	
	14	Soak nozzles before each new lot	0	1	N	0/N = No; 1/Y = Yes	
	15	Cost costos istorial	1	0000	0000	Connecto (0000- Diaphia)	~

FIGURE 3-37: Modifying the value of an option

# CHAPTER 4 System Setup

# Chapter Outline

This chapter discusses P9000's system setup. It covers the following topics:

- P9000 system setup
- Customizing P9000's general settings
- Customizing network communication
- Running remote component exercise
- Customizing pump settings
- Managing user accounts
- Customizing system messages
- Miscellaneous configurations

# P9000 System Setup

The P9000 comes pre-configured according to customer requirements. This allows the customer to run the system straight out of the package, without having to configure the system from scratch.

However, if you want to change the default settings to accommodate your changing production requirements, you can customize the system settings anytime from the Setup page, which allows you to customize the configuration of various system settings.

# Customizing P9000's General Settings

The General page shows the available modules on the P9000, as shown in Figure 4-1.

EMIK	ONDUCTOR	Count: 7	37:17	2012 ' PM	@smar	t <mark>P</mark> ro P9000	Role: Super User Logon: 0000:02:07:46	enanco
Ge	ceral 🙍 Communicat	ion 📡 RemoteCE 🗸	Pump	o settings	() Diagnostic Times	🔏 User Management 🔀 Me	essages Config 🧳 Miscellaneous	
able	/ Disable modules:	1000 ECON (1000	-	Sharing	modules:		Process	
1.00	Module name	State	-		Module name	State	Confirm using default BatchID.	
V.	Robot	Enabled		N.	Coater1	Shaing		
1	Indexer1	Enabled		1	Coater2	Sharing	Commin download recipe.	
V	Indexer2	Enabled			Dev1	Sharing	V Show warning message when enter "System".	
7	Coater1	Enabled			Dev2	Sharing	Centering wafers by aligner.	
V	Coater2	Enabled			VPrime	Sharing		
V	Dev1	Enabled			Hpo1	Sharing		
V	Dev2	Enabled			Hpo2	Shating		
2	VPrime	Enabled	1		Hpo3	Sharing		
1	Hpo1	Enabled			Hpo4	Sharing		
V	Hpo2	Enabled	1		Chill1	Sharing		
V	Hpo3	Enabled	1		Chil2	Shating		
7	Hpo4	Enabled		12	Chill3	Sharing		
V	Chill1	Enabled			Chill4	Sharing		
7	Chill2	Enabled			Chill5	Sharing		
V	Chil3	Enabled	1	IZ.	Algner	Sharing		
7	Chil4	Enabled						

FIGURE 4-1: Configuring General settings

The General page shows the following three panes (from left to right):

- Enable/Disable Modules
- Sharing Modules
- Process

The following paragraphs discusses each of the sections of the General page.

# **Enable/Disable Modules**

The Enable/Disable Modules pane shows all modules available on the P9000. It also shows which modules are enabled (checked) or disabled (unchecked). By default, all modules are enabled, meaning they are available for use. If, for some reason, a certain module becomes unavailable or you do not want to use them, you can make them unavailable by un-checking the corresponding check boxes.

It is important to know that changes you make in here will affect the recipe you select. For instance, if you disable Coater 1 which is part of a recipe you choose to use, then you must modify the recipe by replacing Coater 1 with Coater 2 before you start the wafer-processing operation. Otherwise, the system will encounter an error and cannot proceed until after you have modified the recipe accordingly.

# **Sharing Modules**

The Sharing Modules pane shows which modules are or are not shared. The P9000 allows two concurrent wafer-processing operations. Sharing a module means that the module can be used by both processes. By default, all modules are shared (checked), but, if you do not want certain modules to be shared, you can uncheck the corresponding check boxes.

## Processes

The Process pane shows four system processes, as described below. You can enable or disable these processes by checking or un-checking their corresponding check boxes.

• Confirm using default batch ID — If selected, the system will prompt you to use the default batch ID when no batch ID is specified prior to the start of an operation.

- Confirm download recipe If selected, the system will display a confirmation message when a recipe has been downloaded.
- Center wafers by Mechanical Centering If selected, the system will center wafers using the Mechanical Centering module.

# Configuring Network Communication

The Communication page shows P9000's network communication settings, such as its IP address and port number. You can open the Communication page by clicking the Communication tab across the top of the Setup page.

The P9000 communicates through its default settings, and these settings should not be changed.

CED SmartPro P9000	) - Version 2.1.1742.	93 (iCore.Multiwa	fers - New Algorith	m)			
	Count: 0	10/28/2013 2:39:43 PM RESET SYSTEM		Pro P900	00 😰	Name: Admin Role: Administrator In: 0000:01:03:07	Maintenance
🥶 General 🗐 Timing ,	/ Speeds	Man Can O U	Communication munication area default settings. See the following setting Address: 192 Port: 52031	User Accourts	Alam Message	s	
🕐 Main 1	System 🧧	Recipes	Datalog	Setup	👍 Ala	rms 💋 Siler	ve 👔 Help

FIGURE 4-2: Configuring network communication
## Performing Remote Component Exercise

The Remote CE page allows you to set up remote component exercises, as shown in Figure 4-3. The page has two communication options for remote component exercise: USB and WiFi. By default, the P9000 uses USB for remote component exercise, but you can switch to WiFi using the following procedures:

- 1. Click the WiFi Connect radio button.
- 2. Specify the IP address.
- 3. Select a port number.
- 4. Click Apply.

To start a remote component exercise:

- 1. Select a Remote CE Communication option.
- 2. Click Start.
- 3. Once the exercise has started, you can stop it by clicking **Stop**.

martPro P9000 - Build 2012.9.22 - 2.42 (Coreh	ultiWafer2_1)	
C & D Connected Count: 7 EMICONDUCTOR	09/22/2012 5.39:16 PM @ smartPro P90	000 Name: CDAdmin Role: Super User Legon: 0000:02:03:45
General 🗴 Communication 😵 RemoteCl	C Pump settinge Diagnostic Times & User Managemer Remote Component E	nt 💥 Mensages Carlig 🦸 Macetareoux Exercise
	START	OP
	Remote CE communication	
	USB Cannect. Wri Cannect.	ected
	Address: 127 . 0 . 0 . Pot: 52033 .	1
	Apply Apply	

## Customizing Pump Settings

The P9000 comes with default pump configurations based customer requirements. This enables customers to put the system into production right away without having to configure the pumps. However, if you want to create custom pump configurations of your own, you can easily do so on the Pump Settings page.

## **Accessing the Pump Settings Page**

To access the Pump settings page:

- 1. From the menu bar, click **Setup**. The Setup page opens.
- **2.** From the top of the Setup page, click Pump settings. The Pump settings page opens. See Figure 4-4.

	2012-10-12 - 14.30 (0010	willing water 2_2)					(CL	
	Count: 1028	10/23/2012 5:56:34 PM	@sma	rtPro P9	0000	Name: CDAdmin Role: Super User ogon: 0007:08:43:36	Syst	em Erro
🖳 General 🚺 Commun	nication StremoteCE	Ø Pump settings	Olagnostic Ta	mes 🔏 User Man	agement X Mess	sges Config 🧳 Miscellaneo	rus	
Controller	s:			New Controller		New Map	Dele	le Mapping
No Pump Controller	Type Addr	ess RS-232 Port	RS232 State Ac	id Pump Delete	Pump Device	Outp	ut Module	Disp. Nr
No Pump Controller	Pump Dev	ce Unit Max P	ressure State	Delete				

FIGURE 4-4: The Pump settings page

## **Creating New Pump Controllers**

A pump controller is like a container or folder that holds information about the pumps. It provides an easy way to organize the pumps used for wafer processing. The P9000 comes with two types of pumps: Cybor and IDI. By default, the system automatically names the pump controller with either Cybor or IDI, depending on which pump controller you choose, unless you want to use a custom name of your own.

To create a new pump controller:

1. On the Pump settings page, click **New Controllers.** The Create New Pump Controller dialog box opens. See Figure 4-5.

Select a	kind of pump	controlle
Cybor	IDI-300	Close

FIGURE 4-5: Select a pump controller type

**2.** Click to select a pump controller, e.g., Cybor. The Pump Controller dialog box opens. See Figure 4-6.

D	Outher Centreller
rump controller hame.	
Pump controller type:	Cybor -
RS-232 Port:	COM3 -
Bus Address:	5
	Save
	Cancer



- **3.** Enter a unique name for the pump controller or simply accept the name the system automatically creates for you.
- 4. select a RS-232 port.
- 5. Select a BUS address.
- 6. Click Save.
- **7.** When the confirmation message shows up, click **Yes.** The newly created pump controller shows up in the Controllers pane of the Pump settings page.

Adding Pumps to a Pump Controller

Once you have created a pump controller, the next step is to add pumps to it.

To add pumps to a pump controller:

1. On the Pump settings page, click **Add Pump**, as shown in Figure 4-7.

imartPro P9000 - Build 2012.	10.12 - 14.58 (CoreM	ult/Wafer2_1)						6	
	Connected	10/23/2012 5:59:35 PM	@ sma	artPro	9000	Name: C Role: Su Logon: 0007:0	DAdmin per User 8:46:37	Syst	em Erro
🗄 General 🔳 Communicatio	n 📡 RemoteCE	🍠 Pump settings	() Disgnostic	Times 🔓 User	Aanagement 🔀	Messages Config 🚽	Miscellaneous		
Controllers:				New Controller			New Mapping	Delet	te Mapping
No Pump Controller	Type Address	RS-232 Port	RS232 State	Add Pump Dele	e Pump Devic	e	Output	Module	Disp. No
<sup>D</sup> ump Devic	es:								
No Pump Controller	Pump Device	Unit Max P	ressure State	e Dele	e				
Main See	Sustem	Passing	0			A CONTRACTOR OF THE	-		1 201010

FIGURE 4-7: Adding a pump to pump controller

 In the Pump Device Builder dialog box, make the desired selections and click Save. See Figure 4-8.

Pump type:*	M5000S (10 ml	, 16 ml,	24 ml)
Unit:	Pump 1 -		
Type:	10 ml -		
	6		



**3.** When the confirmation message appears, click **Yes.** Figure 4-9 shows the Pump settings page with two pump controllers configured and two pump devices in one controller.

	all consists t	10/22/2012				e (ram) N	ame: CDAdmin		-
CED	Count: 1028	6:05:32 PM	© S IT	artPr	o P900	C Logon: 0	ole: Super User 007:08:52:34	Syste	em Erro
🖞 General 🙍 Communicat	ion 📡 RemoteCE 🤇	🖉 Pump setting	9ª 🕢 Disgnost	ic Times 🔓	User Management	🔀 Messages Conf	ig 🦸 Miscellaneous		
Controllers	:			New Cont	roller		New Mapping	Delet	e Mapping
No Pump Controller	Type Address	RS-232 Port	RS232 State	Add Pump	Delete Pung	p Device	Output	Module	Disp. N
1 Cybor Controller	Cybor 5	3	Opened	Add Pump	Delete				
2 IDI-300 Controller	101-300 22	ä	Oased	Add Pump	Delete				
Pump Devi	ces:	164 10-	- Parrie		Debte				
Dump Devie	Ces: Pump Device	Unit Mas	x Pressure St	ale	Delete				
Pump Devi No Puro Controller 11 Cyber Controller	CES: Pump Device M50005	Unit Mas Pump 1 10	x Pressure Si © De	ate	Delete Delete				
Pump Devie No Pure Controller Cytor Controller 2 IDI-300 Controller	Ces: Auto Device MSCOOLS M200	Unit Mas Pump 1 10 Unit A 6	x Pressure St Dia Dia Dia	ale iconnected iconnected	Delete Delete Delete				
Pump Devie No Ruro Controller 1 Quar Controller 2 IDI-300 Controller	Ces: Pure Device MS005 M300	Unit May Pump 1 10 Unit A 6	x Pressure 9 Cm © De	ate	Doiete Deiete				

FIGURE 4-9: Pump settings page with sample pump controllers and pumps

## **Linking Pumps to Modules**

Pumps are closely associated with certain modules. They discharge chemicals onto wafers while they are being processed on a module. Once you have created pump controllers and added the pumps to them, the next thing you need to do is to link the pumps with modules. In this way, you tell the system what pump to use with what module or modules.

To link a pump with modules:

1. On the right side of Pump settings page, click **New Mapping.** See Figure 4-10.

C &		Connected Int: 1028	10/23/2012 6:05:32 PM	@ sm	artP	ro P9	0000 💽 No Ro Logon: 00	ame: CDAdmin sle: Super User 207:08:52:34	🥃 System Erro
Seneral	Communication	SemoteCE	🖉 Pump settin	98 🕢 Disgnosti	c Times S	User Mane	igement 🔀 Messages Config	g 💰 Miscellaneous	
Cont	rollers:				New Cor	troller		New Mapping	Delete Mapping
No Pump (	Controller	Type Addres	s RS-232 Port	RS232 State	Add Pump	Delete	Pump Device	Output	Module Disp. No
1 Cybor C	iontroller	Cybor 5	3	Opened	Add Pump	Delete			
2 101-300	Controller	IDI-300 22	3	Cosed	Add Pump	Delete			
1 CyborC	ortroller	M5000S	Pump 1 10	• Do	connected	Delete			
2 IDI-300	Controller	M300	Unit A 6	© De	connected	Delete			

FIGURE 4-10: Mapping pumps with modules

**2.** In the Pump Output Mapping dialog box, select a pump controller. See Figure 4-11.

Pump Output	Mapping
Pump Device:	·
Pump output:	Cybor Controller - M5000S - Pump 1 IDI-300 Controller - M300 - Unit A
Module:	-
Dispense:	•
	Save Cancel

FIGURE 4-11: Selecting a pump device

**3.** Select a module. See Figure 4-12.

Pump device:*	Cybor Control	ler - M500	0S - Pu	mp 1
Pump output:	Output 1	*		
Module:				
Dispense:	Coater1 Coater2			
	Dev1			

- FIGURE 4-12: Selecting a module
- 4. Select a dispense. See Figure 4-13.

🔞 Pump Output	Mapping	
Pump device:*	Cybor Controlle	ər - M5000S - Pump 1 🔹
Pump output:	Output 1 -	
Module:	Coater1 -	
Dispense:	Dispense 1 Dispense 2 Dispense 3	Save Cancel

FIGURE 4-13: Selecting a Dispense.

- 5. Click Save.
- **6.** When the confirmation message appears, click **Yes.** Figure 4-14 shows the mapping between the pumps and modules.

EM		Connecter Count: 1028	d	10/23/201 6:09:39 PI	2	òsп	artPr	o PS	Name C Role: St Logon: 0007:0	:DAdmin iper User 8:56:41	Syst	em Erro
-	ieneral 💼 Communica	tion 📡 Remi	oteCE	🌮 Pump se	tings 🧿	Diagnost	ic Times 🔓	User Mani	agement 🔀 Messages Config 🧃	Macellaneous		
C	ontrollers	:					New Corr	troller		New Mappin	Delet	Mapping
No	Pump Controller	Туре	Address	RS-232 Pc	st RS	232 State	Add Pump	Delete	Pump Device	Output	Module	Disp. N
01	Cybor Controller	Cybor	5	3	· Ope	ned	Add Pump	Delete	Cybor Controller - M50005 - Pump	1 1	Coater1	1
12	IDI-300 Controller	IDI-300	22	3	© 0o	ed	Add Pump	Delete	IDI-300 Corarolier - M300 - Live A	2 1	E Conter?	2
No	Pump Controller	Pum	p Device	Unit	Max Pressu	e S	late	Delete				
31	Cybor Controller	M500	105	Pump 1 1	0	• 5	scorrected	Delete				
02	IDI-300 Controller	M300		Unit A		0 0	sconnected	Delete				

FIGURE 4-14: Pumps linked to modules

## Managing Users

Access to the P9000 is password-protected. Every user should have a user account with valid user name and password in order to log onto the P9000 operating console.

The system administrator can create as many user accounts as needed. Prior to creating user accounts, the administrator should define different user roles and assign proper privileges to each of them. Once all the roles are properly defined, it is much easier to assign them to user accounts.

## **Opening the Manage User Page**

Top access the Manage User page:

- 7. From the navigation bar, click the Setup button. The Setup page opens.
- 8. From the Setup page, click the User Management tab. See Figure 4-15.

imarti	Pro P9000 - Build 2	2012.9.22 - 2.42 (Co	reMultiWafer2_1)						
EMIK		Connected Count: 7	09/22/2012 5:46:51 PM	©smart	Pro	2	Logon: 00	me: CDAdmin le: Super User 000:02:17:20	😑 Maintenanc
Ger	veral 🔳 Commu	ication 📡 Remot	teCE Ø Pump settings	() Diagnostic Times	🖇 User M	anagement 🔀 Mer	ssages Config 🚽	Miscellaneous	
ser list:					User rol	les:			
No	User name		Role	Status	No	Role name		Description	1
	Admin		Testing		1	Administrator		Full rights	
	Engineer		Engineer		2	Engineer		All rights (exc	epts user edit)
	Operator		Operator		3	Operator		Run process	and view reports only.
					4	Testing			
						Water tott. Waters continuati System Pacopes (view) Context Context new Programs (View) Context new Programs (View) Context new Programs (View) Context new Programs (View)	on. & recipe sharing		
	New	Edit	Delete	P		P	Edit	Delete	
e.	main	Jan Syanam	C reciper	L balancy		Secup.	- Adames	IN A STATE	
-									

FIGURE 4-15: The User Management page

### About the User Management Page

As illustrated in Figure 4-16, the User Management page has two panels: left and right. The left panel lists all available user accounts, showing the user name and role of each account, whereas the right panel provides a brief description of the roles and their privileges.

Each of the panels are some buttons for creating, editing, and deleting users or roles, respectively.

## Creating and Defining User Roles

Creating and defining user roles is the first step in creating user accounts.

To create a user role:

1. Under User roles panel, click the **New** button. The User Role dialog box opens. See Figure 4-16.



FIGURE 4-16: Creating and defining a user role

2. Enter a unique name for the role.

- 3. Enter a brief description of the role.
- 4. Check the privileges to be granted to the role.
- 5. Click the **Save** button.

#### **Modifying User Roles**

Editing a user role involves changing the role name, description, and/or privileges.

To edit a user role:

- 1. From the User roles panel (Figure 4-16), highlight the user role of interest.
- 2. From the bottom of the panel, click the **Edit** button.
- 3. Make the desired changes.
- Click Save As to save the modified user role under a different name, or Save to save it under the same role name. See Figure 4-17.



FIGURE 4-17: Modifying a user role

### **Deleting User Roles**

Care must be taken to keep the User Management page nice and clean so that you can easily find what you need. For that reason, user roles that are no longer needed should be deleted in order to reduce the page clutter.

To delete a user role:

- 1. From the User roles panel (Figure 4-15), highlight the user role of interest.
- From the bottom of the panel, click the **Delete** button. A confirmation message window opens. See Figure 4-18.



FIGURE 4-18: Confirming to delete a user role

3. Click **Yes**. The user role will be deleted after the page refreshes.

## Creating User Accounts

Once you have created and defined the user roles, you can easily create user accounts.

To create a user account:

- 1. Under the User list panel, click the **New** button. The New User dialog box opens.
- 2. Enter a unique name for the account.
- 3. Create a password for the account.
- 4. Confirm the password by entering it for a second time.
- 5. Click the Role drop-down menu and select a user role.
- 6. Add a brief description about the account.

7. Click **Save**. See Figure 4-19. The new account shows up under Account list on the User Management page (Figure 4-15).

User name:		
Password:		
Confirm:		
Role:		-
Description:		
Save As	Save	Close

FIGURE 4-19: Creating a user account

## **Modifying User Accounts**

You can modify the configuration of a user account when the responsibility of the account user has changed.

To modify a user account:

- 1. From the User list panel of the User Management page (Figure 4-15), highlight the user account of interest.
- 2. Click the Edit button below the panel. The Edit User dialog opens.
- 3. Make the desired changes.
- 4. Click **Save As** to save the modified user account under a different account name, or **Save** to save it under the same name.

#### Note:

If you want to modify the privileges associated with the user role, you should modify the role first before making changes to the user account. For instructions on how to modify a user role, refer to "Modifying User Roles" on page 69.

## **Deleting User Accounts**

You can delete the user accounts that are no longer needed.

To delete a user account:

- 1. From the User list panel of the User Management page (Figure 4-15), highlight the user account of interest.
- 2. Click the **Delete** button below the panel. A confirmation message shows up.
- 3. Click **Yes**. The user account will be deleted from the User list.

## Configuring System Messages

The Message Configuration page shows the default system messages, as shown in Figure 4-20.

MICON	Count: 7 5	9/22/2012 52:33 PM	SmartPro P9000	🥪 Maintenanc
General	Communication S RemoteCE	Pump settings	🗿 Diagnostic Times 🥈 User Management 💥 Messages Config 🦸 Miscellaneous	
tsil eçese			Details	Code
lo. Me	ssage	Type	Please reset system to initialize.	1
Pleas	se most system to initialize.		Please reset system to initialize	Default
Pleas	se select recipe.			
Place	e new cassette on to start.			
Cann	not reset system - Robot busy.			
(0) n	ot ready - Reset?			
Cann	ot download program for (0).			
Cann	ot enter component exercise > Process running?			
Cann	ot enter component exercise - indexer at botto .			
Open	ation aborted - Retrieving wafer			
Wati	ing for reset			
Wati Tran	ng for reset sfer stop - Resume?			
Wati Trans Cann	ing for reset afer atop - Resume? iot calibrate travel time – Process running?			
Wati Trans Cann Cann	ng for reset sfer stop - Resume? not calibrate travel time – Process running? not calibrate travel time – Currently in Compone			
Wati Tran Cann Cann Mach	ing for reset afer stop - Resume? iot calibrate travel time – Process running? iot calibrate travel time – Currently in Compone nine power on, all modules have initialized.	System		
Wati Trans Cann Cann Mach Syste	ing for reast der stop Resume? tot calibrate travel time – Process running? ot calibrate travel time – Currently in Compone ine power on, all modules have initialized. m purge failures?	System System		
Wati Tran Cann Mach Syste	ing for reset der stop - Resume ? ot calibrate travel time - Poccess running ? ot calibrate travel time - Currently in Compone inine power on, all modules have initialized em purge fakures - Resume ?	System System System		
Wata Trans Cann Cann Mach Syste	ing for reset der stop - Resume ? ot calibrate travel time - Process running ? ot calibrate travel time - Currently in Compone time power on, all modules have initialized im purge failures ? im purge failures - Resume ?	System System System	-	
Wata Trans Cann Mach Syste	ing for reset der stop - Resume ? ot calibrate travel time - Poccess running ? ot calibrate travel time - Currently in Compone inne power on, all modules have initialized. im purge failures - Resume ?	System System System	-	Save

FIGURE 4-20: Configuring system messages

## **Modifying Existing Messages**

You can modify the existing messages using the following procedures:

- 1. From the Message List on the left, click the message of interest.
- 2. The message will show up in the Details pane on the right.
- 3. Highlight the words in the message you want o change.
- 4. Override the words with new ones.
- 5. Click Save.

## **Creating New Messages**

You can also create new messages using the following procedures:

- 1. In the blank space on the right, type the message.
- 2. Click Save.

## Miscellaneous Configurations

The Miscellaneous page offers some more configuration options, as shown in Figure 4-21.

MICONDUCTOR		Logor. C	AUU.00.20.35
General 🙍 Communication 🔗 Pump or	ettings 🔓 User Manageme	nt 💥 Messages Cantig 🦸 Macellaneous	
larathon Test		Data Logs	Miscellaneous
Option	Counter	Auto out data logs retention to 3 Months -	Reset wafers counter
💌 By Wafers: 500 🗧 (wafers)	20 wafers		
By Cassettes: 100 (cassettes)	0 cassettes	Clear all datalogs	Show debug viewer.
() By Timer: 2000 († (minutes)	0 days, 1 hours, 0 min		
Unlimited			

FIGURE 4-21: Configuring miscellaneous settings

The Miscellaneous page has the three sections:

- Marathon Test
- Data Logs

Miscellaneous

#### **Setting Up Marathon Tests**

The Marathon Test section contains controls for configuring and running system marathon tests.

- By Wafers Sets up a marathon test by the number of wafers. The test stops once the system has processed the set number of wafers.
- By Cassettes Sets up a marathon test by the number of cassettes. The test stops once the system has processed the set number of cassettes (of wafers).
- By Timer Sets up a marathon test by the number of minutes. The test stops once the system has reached the set number of minutes.
- Unlimited Sets up a marathon test that will last forever.
- Start Marathon 1 Starts a marathon test 1 (on Indexer 1).
- Start Marathon 2 Starts a marathon test 1 (on Indexer 2).
- Clear Erases the current readings on the counter.

#### Managing Data Logs

The Data Logs section provides some basic control on the data logs in the system's database.

- Auto cut data log retention to Check this check box to let the system retain the data logs for the period of time you specify. The system will automatically remove from the database data logs that are beyond the specified time frame.
- Clear all data logs Clears all data logs.

#### Miscellaneous Settings

This section provides the following controls:

- Reset wafer counter resets the wafer counter to 0 (zero).
- Show debug viewer shows the debug window.

# CHAPTER 5 Viewing & Managing Reports

## **Chapter** Outline

This chapter discusses P9000's Data log page, which contains various reports that the system is able to generated. It covers the following topics:

- Accessing the Data log page
- Types of reports
- Data log page UI components
- Alarm Reports
- Events Reports
- Wafer Lost Reports
- User Reports
- Batch Reports
- Batch Details Reports

## Access the Data log Page

The P9000 has the capability to capture various system data and present them in the form of reports. The reports are organized into six major categories, each of which is represented by a tab on the Data log page. You can access the Data log page by clicking **Data log** on the Menu bar.

## Types of Reports

Table 5-1 briefly describes the six types of reports that the P9000 is able to generate.

Report Category	Description
Alarm Reports	Shows alarms the system has generated.
Event Reports	Shows data of events the system has performed.
Wafer Lost Reports	Shows the statistics of lost wafers — those that the system was unable to process due to human or mechanical error.
User Reports	Shows activities on the system by user account.
Batch Reports	Shows data by batch ID.
Batch Details Reports	Shows batch data in greater details.

TABLE 5-1: Description of P9000 Cluster System Data Reports

## Datalog Page UI Components

Figure 5-1 highlights the major UI components common to all reports pages. Table 5-2 describes each of these components.

NDUCTOR	Count: 7	09/22/2013 5:19:50 PM	() ()	smai	rtPro P9000	Rate: CDAdmin Role: Super User Logon: 0000:01:50:19	🨑 Maintenan
ts Event reports	WaferLost User repo	ats Batch reports	Batch details				
on date/time		Filtering condition	onal				
Date	Time Now	Module	ALL MODULES		Ratch ID ALL	RATCHIDS	- 6
8/22/2012 -	5:30:00 PM -0-				<b>3</b>		_
	Carton and a second second	Recipe Name	ALL RECIPES				• Export
9/22/2012 -	4:56:41 PM	Alarm				Search when ty	ping
		ii -					
ate/Time	BatchID Reci	pe Name	Module	Witt	Alarm Message	Memo	
22/2012 4:54 PM			Hpo2	0	Finish set temperature		
22/2012 4:54 PM			Hpo1	0	Rinish set temperature		
22/2012 4:54 PM			Hpo3	0	Finish set temperature		
19/2012 10:53 AM	4		Indexer1	0	The cassette is not in place?		
18/2012 6:37 PM			Indexer2	0	The cassette is not in place?.		
18/2012 6:37 PM			indexer2	0 *	The cassette is not in place?.		
18/2012 6.37 PM			Indexer2	0	The cassette is not in place?.		
18/2012 6:29 PM			Indexer1	0	The cassette is not in place?.		
18/2012 6.29 PM			Indexer2	0	The cassette is not in place?.		
18/2012 11:54 AM	4		Indexer2	0	The cassette is not in place?.		
18/2012 11:53 AM	4		Indexer1	0	The cassette is not in place?		
17/2012 12:03 PM	4		Indexer2	0	The cassette is skewed when proc	essing.	
17/2012 11:40 AM	4		Algner	0	Undefined status code 10		
17/2012 11:38 AM	4		Algner	0	Undefined status code 3		
	the sevent motorts and date./time bute B/22/2012 c sevent motorts B/22/2012 c sevent motorts b/22/2012 c sevent motorts b/22/2012 c sevent sevevent sevent se	Imports     WorkerLoat     User reports       on date-Arme     Tme     Now       8/22/2012     5:30:00 PM     ≥       9/22/2012     5:30:00 PM     ≥       9/22/2012     4:56:41 PM     ≥       202/2012     4:57 PM     B       B/2012     1:53:7 PM     B       B/2012     1:54:7 PM     B       B/2012     1:53:7 PM     B       B/2012     1:53:7 PM     B       B/2012     1:53:7 AM     17/2012       1:203     2:03 PM     B       B/2012     1:53:7 AM     17/2013       1:7/2012     1:40:AM     14/2004	Back time     Norm     Partner     Partner     Partner       0 date filme     Time     Norm     Filtering condition     Module       8/22/2012     Time     Norm     Filtering condition     Module       8/22/2012     4/56/41 PM     More     Alorm     Alorm       ater/Time     BatchID     Recipe Name     Alorm       22/2012     4/56/41 PM     Partner     Alorm       22/2012/2/54/FM     E2/2012/57 PM     E2/2012/57 PM     E2/2012/57 PM       18/2012/6/37 PM     E2/2012/6/37 PM     E2/2012/6/37 PM     E2/2012/6/37 PM       18/2012/6/37 PM     E2/2012/6/37 PM     E2/2012/6/37 PM     E2/2012/6/37 PM       18/2012/6/20 PM     E2/2012/1/54 AM     E2/2012/6/20 PM     E2/2012/6/20 PM       18/2012/6/20 PM     E2/2012/6/20 PM     E2/2012/6/20 PM     E2/2012/6/20 PM       18/2012/6/20 PM     E2/2012/6/20 PM     E2/2012/6/20 PM     E2/2012/6/20 PM       18/2012/6/20 PM     E2/20 PM     E2/20 PM     E2/20 PM       18/2012/6/20 PM     E2/20 PM     E2/20 PM     E2/20 PM       18/2012/20 PM <t< td=""><td>Batch reports     Batch reports     Batch details       on date.time     Time     Now     Resign conditional       B222/2012     5 3000 PM     P     P       522/2012     4 56.41 PM     P     Resign conditional       Model     ALL MODULES.     Respensive     Alom       aterTime     BatchID     Recipe Name     Module       22/2012.4 54 PM     Hoto2     22/2012.4 54 PM     Hoto2       22/2012.4 54 PM     Hoto2     22/2012.4 54 PM     Hoto2       22/2012.4 54 PM     Hoto2     22/2012.4 54 PM     Hoto2       22/2012.4 54 PM     Hoto2     18/2012 63 PM     Indexer2       18/2012 63 PM     Indexer2     Hotoser2     18/2012 63 PM     Indexer2       18/2012 63 PM     Indexer2     18/2012 63 PM     Indexer2       18/2012 62 PM     Indexer2     18/2012 13 AM     Indexer2       18/2012 13 AM     Indexer2     18/2012 13 AM     Indexer2       18/2012 12 10 FM     Indexer2     19/2012 114 AM     Indexer2</td><td>Batch reports     Batch details       on date-time     Now     Restorm and the time of the time of time o</td><td>tree Vork vork vork vork vork vork vork vork v</td><td>Batch reports   Batch details     an date fime   Time   Now     B222/2012   Time   Now     B222/2012   Time   Now     B222/2012   5/30.00 PM ≥   Recipe Name     Alter   Alter   Now     B222/2012   4/56.41 PM ≥   Recipe Name     Alter   Alter   Now     S22/2012   4/56.41 PM ≥   Now     Search when by   Now   Search when by     ater/Time   BatchID   Recipe Name   Module   Wf#   Alter Message   Memo     22/2012/4.54 PM   Hoo1   0   Finish at temporature   Search when by     22/2012/4.54 PM   Hoo1   0   Finish at temporature   Search when by     19/2012/0.53 AM   Indexer1   0   The casette is not in place?   Ite casette is not in place?     18/2012/0.53 FM   Indexer2   0   The casette is not in place?   Ite casette is not in place?     18/2012/0.52 FM   Indexer2   0   The casette is not in place?   Ite casette is not in place?     18/2012/0.52 FM   Indexer2   0   The casette is not in place?</td></t<>	Batch reports     Batch reports     Batch details       on date.time     Time     Now     Resign conditional       B222/2012     5 3000 PM     P     P       522/2012     4 56.41 PM     P     Resign conditional       Model     ALL MODULES.     Respensive     Alom       aterTime     BatchID     Recipe Name     Module       22/2012.4 54 PM     Hoto2     22/2012.4 54 PM     Hoto2       22/2012.4 54 PM     Hoto2     22/2012.4 54 PM     Hoto2       22/2012.4 54 PM     Hoto2     22/2012.4 54 PM     Hoto2       22/2012.4 54 PM     Hoto2     18/2012 63 PM     Indexer2       18/2012 63 PM     Indexer2     Hotoser2     18/2012 63 PM     Indexer2       18/2012 63 PM     Indexer2     18/2012 63 PM     Indexer2       18/2012 62 PM     Indexer2     18/2012 13 AM     Indexer2       18/2012 13 AM     Indexer2     18/2012 13 AM     Indexer2       18/2012 12 10 FM     Indexer2     19/2012 114 AM     Indexer2	Batch reports     Batch details       on date-time     Now     Restorm and the time of the time of time o	tree Vork vork vork vork vork vork vork vork v	Batch reports   Batch details     an date fime   Time   Now     B222/2012   Time   Now     B222/2012   Time   Now     B222/2012   5/30.00 PM ≥   Recipe Name     Alter   Alter   Now     B222/2012   4/56.41 PM ≥   Recipe Name     Alter   Alter   Now     S22/2012   4/56.41 PM ≥   Now     Search when by   Now   Search when by     ater/Time   BatchID   Recipe Name   Module   Wf#   Alter Message   Memo     22/2012/4.54 PM   Hoo1   0   Finish at temporature   Search when by     22/2012/4.54 PM   Hoo1   0   Finish at temporature   Search when by     19/2012/0.53 AM   Indexer1   0   The casette is not in place?   Ite casette is not in place?     18/2012/0.53 FM   Indexer2   0   The casette is not in place?   Ite casette is not in place?     18/2012/0.52 FM   Indexer2   0   The casette is not in place?   Ite casette is not in place?     18/2012/0.52 FM   Indexer2   0   The casette is not in place?

FIGURE 5-1: Reports Page Major UI Components

#	UI Component	Description
1	Report Menu	Displays the types of reports that the system generates. Clicking a tab opens the corresponding report.
2	Filter Date/Time	Allows you to view reports for a specific time frame by selecting the From: and To: date and time. Clicking <b>Now</b> allows you to view the most recent reports.
3	Filter Conditional	Allows you to view alarms by module, recipe, batch ID, or text in a alarm message. Ticking the Search when typing check box will allows the system to search the alarm data- base as you are typing.

TABLE 5-2: Reports	Page	Common	UI	Components
--------------------	------	--------	----	------------

#	UI Component	Description
4	Report Panel	Displays the content of the report being selected. By default, this part of the screen is empty when the Reports screen opens because no report is being selected. The screen will also be empty if the type of report you select contains no data at all.
5	Page Control	Allows you to specify the number of logs per page, see the total number of entries in a report, and choose the page of a report to display.
6	Export	Exports the report currently displayed on the screen in Microsoft Excel format.

TABLE 5-2: Reports Page Common UI Components

## Alarm Reports

The Alarm Reports page shows alarm messages the system has generated. You can view alarm reports by selecting the Alarm reports tab, as shown in Figure 5-1. However, the Alarm reports page will show up blank (without any entry) if the system has not generated any alarm.

Table 5-3 describes the information shown on the Alarm Reports page.

TABLE 5-3: Data in Alarm Reports

Data	Description
No.	The sequence number of an alarm on the screen.
Date/Time	The date and time when an alarm was triggered.
Batch ID	The ID number for a batch of wafers. It shows 000000000000000000000000000000000000
Recipe Name	The name of the recipe used.
Module	The system module, i.e., CHILL, VP, CTPC, etc. Wafer
#	The Index number that the Indexer assigned to a wafer
Alarm Message	The message associated with a particular alarm
Memo	The memo entered by an operator, if applicable.

## **Event Reports**

The Event Reports lists all the events the system has logged. You can open the Event reports page by selecting the **Event reports** tab. Figure 5-2 shows the Event Reports page.

		Connected Count: 7		09/22/201 5:24:58 PM	@smartPro P9000					Name: CD Role: Sup Logon: 0000:01:	🔒 Maintenance			
larm re	ports Event reports	WaferLost	User reports	Batch reports	Batch d	etals								
121 04	ter on date time			Ellaring coods	land									
2.11	Dete	Tour	Now	Mad de	(ass and	018.55								
From	8/22/2012 -	5-30-00 PM		module	ALL NO	DULES		• D00	ALL BATC	HIDS	6			
	0/22/2012 •	5.30.00 PM	1	Recipe Name	ALL REG	CIPES			00000000	0000000	0000		Export	
To:	9/22/2012 🕶	2012 × 5:23:33 PM		Event	ſ [				7890 Batch ID MARATHON_TEST					
No.	Date/Time	BatchID	Proces	s Name	Module	Witt	Event#	Operation	Speed (rpm)	) Temp. ("C)	Gap (mm)	Memo	1	
1	9/19/2012 10:54 AJ	4 Batch ID	Recipe 1	H	ipo 1	2	1	Bake	0	0	0	Memo		
2	9/19/2012 10:53 A	H Batch ID	Respe 2	H	ipo2	3	1.	Bake	0	0	0	Мето		
3	9/19/2012 10:53 Al	4 Batch ID	Recipe 1	c	ioater1	2	1	Spin	0	0	0	Memo		
4	9/19/2012 10:53 AJ	4 Batch ID	Recipe 2	e e	lpo2	2	1	Bake	0	0	0	Memo		
5	9/19/2012 10:53 AJ	4 Batch ID	Recipe 2	c	oster2	3	1	Spin	0	0	0	Memo		
5	9/19/2012 10:53 AJ	4 Batch ID	Recipe 2	C	loater2	2	1	Spin	0	0	0	Memo		
7	9/19/2012 10:50 AJ	M Batch ID	Recipe 1	н	ipo1	2	1	Bake	0	0	0	Memo		
8	9/19/2012 10:50 AJ	M Batch ID	Recipe 2	н	ipo2	2	1	Bake	0	0	0	Memo		
9	9/19/2012 10:49 AJ	4 Batch ID	Recipe 1	C	loater1	2	1	Spin	0	0	0	Memo		
10	9/19/2012 10:49 AJ	4 Batch ID	Recipe 2	C	loater2	2	1	Spin	0	0	0	Мето		
11	9/19/2012 10:47 AJ	4 Batch ID	Recipe 1	H	ipo 1	2	1	Bake	0	0	0	Memo		
12	9/19/2012 10:47 AJ	4 Batch ID	Recipe 2	H	ipo2	2	1	Bake	0	0	0	Memo		
13	9/19/2012 10:47 A	4 Batch ID	Recipe 2	c	oater2	3	1	Spin	0	0	0	Мето		
14	9/19/2012 10:46 AI	4 Batch ID	Recipe 1	c	oater1	2	1	Spin	0	0	0	Мето		
15	9/19/2012 10:46 AI	4 Batch ID	Recipe 2	c	loater2	2	1	Spin	0	0	0	Memo		
imited	Lines: 50 •						Total reco	rds: 85				Page: 1		
2	Main	Sys	tem	C Recip	- 1	<b>``</b>	atalog	Setup		Alarms	X Silence	0	Help	

FIGURE 5-2: The Event Reports Page

As seen from Figure 5-2 above, the Event Report contains the following information as described in Table 5-4.

TABLE 5-4: Data in Event Reports

Data	Description
No.	The sequence number of an event.
Date/Time	The date and time when an event occurred.
Batch ID	The ID number for the batch of wafers, or 00000000000000000000000000000000000
Process Name	The name of the process used for an event.

Data	Description
Module	The system module, i.e., CHILL, VP, CTPC, etc.
Wf #	The index number that the Indexer assigned to a wafer.
Event#	The sequence number of an event.
Operation	The type of processing operation used for an event.
Speed (rpm)	The processing speed in terms of revolutions per minute.
Temp. (C)	The temperature in centigrade used for an event.
Memo	The memo the user entered about a particular event, if applicable.

TABLE 5-4: Data in Event Reports

## Wafer Lost Reports

The Wafer Lost reports show data about lost wafers the system generated. You can open the Wafer Lost Reports page by selecting the Wafer Lost tab. Figure 5-3 shows the Wafer Lost Reports page. Table 5-5 describes the information in Wafer Lost Reports.

#### FIGURE 5-3: The Wafer Lost Reports Page

#### TABLE 5-5: Data in Wafer Lost Reports

Data	Description
No.	The sequence number of a log on the current Wafer Lost page.
Date/Time	The date and time when a wafer was lost during an operation.
Batch ID	The ID number for the batch of wafers, or 00000000000000000000000000000000000
Recipe Name	The name of the recipe used.
Module	The system module, i.e., CHILL, VP, CTPC, etc. where the wafer was lost.

Data	Description
Wf #	The index number of a wafer.
Memo	The memo the user entered about a batch, if applicable.

TABLE 5-5: Data in Wafer Lost Reports

## User Reports

The User Reports page shows detailed information about activities based on user account. You can open the User Reports page by clicking the **User Reports** tab. Figure 5-4 shows the User Reports page. Table 5-6 describes the information on the User Reports page.

Semi	C & D	Count: 7	d	09/22/2012 5:28:08 PM		© 5	martPro P9000	Name: CDAdmin Role: Super User Logon: 0000:01:58:37	曼 Maintenanc
larm re	ports Event report	s WaferLost User	reports	Batch reports	Batch de	tals			
12 R	ter Logio Time		Fite	Looo # Time			Filtering conditional		
-		Terro Manuel			-	Now	These sectors and the sector sectors and the secto		
Enne	Uate	Con co pu la l	Error	Little	Time .		ALLUSERS		
cover.	8/22/2012 •	5.30.00 PM	rivin,	8/22/2012 •	5:30:00	I PIM (2)	Liner Action		Export
To:	9/22/2012 👻	5-27:57 PM 🔶	To:	9/22/2012 -	5:27:5	7 PM 🚖		E Search when typing	1
No.	UserName	Time Login	Time	Logout	Logon Time (s)	R.	User Action		-
1	COAdmin	5/15/2012 10:58 PM	9/19/25	012 10:59 PM	20		Clicks on Setup button		
2	CDAdmin	9/19/2012 9:18 PM	9/19/20	012 9.18 PM	10		Clicks on Setup button.		
3	CDAdmin	9/19/2012 9:15 PM	9/19/20	012 9.18 PM	136		Clicks on Setup button.		
4	CDAdmin	9/19/2012 9:12 PM	9/19/20	012 9.13 PM	33		Clicks on Setup button.		
5	CDAdmin	9/19/2012 8:31 PM	9/19/20	012 8:33 PM	122		Clicks on Setup button.		
6	CDAdmin	9/19/2012 8:30 PM	9/19/20	0128:31 PM	59		Clicks on Setup button.		
7	CDAdmin	9/19/2012 5:24 PM	9/19/20	012 5:25 PM	55		Clicks on Setup button.		
8	CDAdmin	9/19/2012 4:33 PM	9/19/20	012 4:34 PM	98		Clicks on Setup button.		
9	CDAdmin	9/19/2012 9:54 AM	9/19/20	012 9:56 AM	82		Clicks on Recipe button.		
10	CDAdmin	9/19/2012 9:31 AM	8/19/20	012 9:33 AM	81		Clicks on Recipe button.		
11	CDAdmin	9/18/2012 11:15 PM	9/18/20	012 11:16 PM	62		Clicks on Recipe button.		
12	CDAdmin	9/18/2012 10:26 PM	9/18/20	012 10.28 PM	96		Clicks on Recipe button.		
13	CDAdmin	9/18/2012 7:14 PM	9/18/20	012 7:14 PM	27		Clicks on Recipe button.		
14	CDAdmin	9/18/2012 7:11 PM	9/18/20	012 7:14 PM	140		Clicks on System button.		
Limited	Unes: 50 -						Total records: 247		Page: 1
2	Main	Sustan		Pasies		-	Datalan Calua	Alarma II Claura	A Hala

FIGURE 5-4: The User Reports Page

TABLE 5-6: Data in User Reports

Data	Description
No.	The sequence number of a log entry on the current User Reports page.
User Name	The name of a user account.
Time Login	The time a user logged in.
Time Logout	The time a user logged out.
Logon Time (s)	The length of time an user stayed logged on.
User Action	The actions a user performed during a particular session.

## Batch Reports

The Batch Reports page lists all the events the system has generated about a particular batch of wafers it has processed. You can open the Batch Reports page by selecting the Batch reports tab. Figure 5-5 shows the Batch Reports page.

EMI	GID	Count:	583	09/19/2013 3:00:45 PM	6	sma	rtPro P	9000		Role: Admin Role: Admin og On: 0000:04:56	:49	Maintenanc
um Re	ports Event Repo	rts Wafer L	ost User Rep	orts Batch Rep	orts							
	er on date Ame			Filtering conditio	col .							
	Date	Time	Now	Ratch ID		ne .		2				
From:	8/19/2013 -	5-30-00 PM	(A)	Daturi 10	ALL BAILT I	U.S.		<u>e</u>				
			- Labor	Recipe Name	ALL RECIPES					-		Export
To:	9/19/2013 🗸	3:00:33 PM	<b>全</b>	Memo						E Search	when typing	
No.	Date/Time	BatchID	Recipe	Name	Cass	Мар	Processed	Alarm	Lost	Unprocessed	Start Time	Finished
	8/29/2013 1:24 PM		DEV DEN	10	Snd_Rcv	0	0	0	0	0	8/29/2013 1:24	PM 8/29/2013 1:2
10	8/21/2013 3:43 PM		SHOW DE	EV .	Snd_Rcv	25	25	0	0	0	8/21/2013 3:20	PM 8/21/2013 3
	8/21/2013 3:19 PM		SHOW DE	EV	Snd_Rcv	20	3	0	0	13	8/21/2013 3:13	PM 8/21/2013 3.
13	8/21/2013 3:06 PM		SHOW DE	EV .	Snd_Rcv	25	25	0	0	0	8/21/2013 2:43	PM 8/21/2013 3:
5	8/21/2013 2:33 PM		SHOW DE	EV	Snd_Rev	24	10	0	0	14	8/21/2013 2:23	PM 8/21/2013 2
	8/21/2013 2:02 PM		SHOW DE	EV	Snd_Rcv	24	2	0	0	22	8/21/2013 1:59	PM 8/21/2013 2
	1 mar. (60 m)				-11		adamada 6					Page 1
								-			,	

FIGURE 5-5: The Batch Reports Page

Table 5-7 describes the information on the Batch Reports page.

### TABLE 5-7: Data in Batch Reports

Data	Description
No.	The sequence number of a log entry on the current Batch Reports page.
Date/Time	The date and time when a batch of wafers was processed.
Batch ID	The ID number for a batch of wafers, or 00000000000000000000000000000000000
	if no batch ID was created
Recipe Name	The name of the recipe used.
Cass#	The cassette number
Map	Number of wafers scanned
Processed	The number of wafers in a batch that were processed.
Alarm	The number of wafer has alarm
Lost	The number of wafers that were lost in a batch
Unprocessed	The number of wafers in a batch that were not processed
Start time	Time process starts
Finished time	Time process finished

This page is intentionally left blank.

**CHAPTER 6** 

## **System Maintenance**

## Chapter Outline

This chapter discusses the system maintenance. It covers the following topics:

- Calibrating the Robot arm positions
- Centering Coaters/Developers/Chill Plates
- Centering the Mechanical Centering
- Centering the Vapor Primer
- Centering Hot Plate Ovens
- Calibrating Hot Plate Oven/Vapor Prime pin height
- Checking Hot Plate Oven/Coaters/Developer exhaust level
- Checking Coater/Developer spin speed
- Checking Developer air ring gap
- Calibrating Hot Plate Oven/Vapor Prime temperature

## System Calibration

All modules on the P9000 are properly calibrated according to customer requirements prior to shipment. Because of this, the system should be ready for use out of the package and no calibration is required.

It is highly recommended users verify appropriate Air ring pressure is established prior to commencing any activities. It is highly recommended users ensure the presence of a wafer on the chuck when dispensing developer.

However, after being put in service in a production environment for an extended period of time, some modules may deviate slightly from their factory settings. As a result, some re-calibration is required in order to correct the deviations to ensure the system's precision and performance.

C & D	Count: 0	EASE RESE	8/2013 53 PM	Smart P	ro <b>P</b> 9000	Name: Admin Role: Administrator Log On: 0000:00:23:17	Maintenan Transfe Stop
Robot 💓 Indexer1	indexer.	2 Coater1	🗈 Coster2 🥌 H	po1 🥌 Hpo2	🥌 Hpo3 🥌 Hpo4	Hpo5 📥 Hpo6 📥 Chill 1	Child Child 4
lodule:	ndexe	er1	Arm:	Cold	Arm 🖌	Cossette 1	Cold Measure Cald Arm
						24	
cuum	Laser	Control				23	W Vacuum Plot 74m
				1		22	Mapping
Vacuum On	Laser On	Get	Big si	ze - 4"	• • • • • • • • • • • • • • • • • • •	21	
						20	
Vacuum Off	Laser Off	Put	Mech	. Center	Centering	19	
						18	
					Dubat.	1/	
Robot Training	Robot Param	sters			Hobot	15	
					Disable Torque	14	
Move To Station Retra	act Pos.	Move Left	Move Up	Move In		13	
					Enable Torque	12	
Move To Get Po	is,	50	50	50 💲		11	
						10	1000
Move To Scan Po	os.	Move Right	Move Down	Move Out		3	indexer
			-		1	7	Reset
Move To Home P	los.	Save Scan Pos	ition Save S	tation Position		5	C. C
	1					5	Till Down
7						4	
	(I) Sta	• C	Reset			3	Map Wafers
100000000							<b>U</b>
ware version.	-						Law and the second seco

System calibrations are carried out on the P9000's System page, which you can open by clicking the System button on the navigation bar, as illustrated in Figure 6-1.

#### FIGURE 6-1: The default System page

As shown in Figure 6-1, the top of the System page is a row of tabs representing all the modules available on the P9000. By default, the Robot tab is automatically selected when the System page opens.

#### Note:

The P9000 is a customized system whose features and functions are based on customer requirements. For this reason, the types of modules and the number of units of a particular module available on the system may differ. The screen shots used in this User Manual were taken from one of the systems and may or may not apply to all P9000s. Refer to your purchase contract for information about the features and functions of your P9000.

## Calibrating Robot Arm Positions

The Robot is an important component of the P9000 system. During wafer processing operations, the Robot uses its arms to get wafers into and out of the system modules (e.g., Cassettes, Coaters, Developers, etc.) and transfers them from one module to another. The precision of the Robot at every move is vital to the operation of the system. Because of this, you must check the position of the Robot in relation to each of the modules to make sure that they work in sync. Calibrate if the positions are off.

Robot position calibration must be done in reference to the modules it interacts with. In this sense, you must calibrate the Robot with every module on the P9000 individually. Furthermore, since the Robot has two arms — Cold/Top and Hot/ Bot(tom), you must calibrate each arm with each module separately, using the same procedures.

#### **Calibrating Robot-Indexer Position**

The P9000 comes with two Indexers, each of which must be calibrated individually against the Robot. For illustration purposes, the following procedures discuss the calibration of the Robot with Indexer 1. You can use the same procedures to calibrate Indexer 2.

It is important to note that you must use the wafer in the first (bottom) slot in the cassette to calibrate the Robot in relation to an Indexer.

To calibrate the Robot-Indexer position:

- 1. Put the test wafer in the first slot on a cassette.
- 2. Place the cassette on an Indexer station. (*Note: You must calibrate both Indexers* 1 and 2, but you can start with any one.)
- 3. From the navigation bar, click System. The System (Robot) page opens.
- 4. For Module, select Indexer1.
- **5.** For Arm, select **Cold/Top.** (*Note: Both arms have to be calibrated. You can start with either one.*)
- 6. On the Cassette, select the first slot.
- 7. At Indexer click "Tilt Down"
- 8. Under Training, click **Move To Get Position.** The Robot now starts to move to its current *get* position.
- 9. Observe the position of the Robot arm.
- If necessary, adjust the Robot arm position by clicking Move Left, Move Right, Move Up, Move Down, Move In, and/or Move Out until the arm is properly positioned.
- **11.** When you are about to save the position, move the arm upward until it touches the back of the wafer.
- 12. Click Save Station Position.
- **13.** Click **Yes** on the message. The arm automatically moves to station retract position.
- 14. Repeat Steps 4 through 13 to calibrate the Robot and Indexer using the **Hot/Bot** arm.
- **15.** After you have successfully calibrated the Robot in reference to Indexer 1, repeat the above steps to calibrate the Robot in relation to Indexer 2.

#### **Calibrating Robot-Indexer Scan Position**

The Robot is equipped with a laser scanner which automatically scans all slots in the Cassette at the start of each session. This enables the system to detect which slots have wafers and which ones are empty. The results are shown in the Cassette on the screen. Because the system always starts the scanning with the first (bottom) slot on the Indexer, make sure that you calibrate the Indexer scan position using a wafer in the first slot on the cassette.

To calibrate the Indexer scan position:

1. Put a test wafer in the first slot of the cassette.

- 2. Place the cassette on the Indexer station.
- 3. From the navigation bar, click System. The System (Robot) page opens.
- 4. Under Training, click **Move to Scan Position.** The scanner on the Robot now moves to face the cassette.
- 5. Under Laser, click **Laser On.** The laser now shines on the cassette near the bottom.
- 6. Check to see if the laser light hits the test wafer in the first slot on the cassette.
- 7. If necessary, adjust the scan position by clicking Move Left, move Right, Move Up, Move Down, Move In, and/or Move Out until the laser hits the wafer in the first slot. (*Note: The Mapping radio button turns yellow when the laser light hits the wafer, which means a good result.*)
- 8. Click Save Scan Position.
- 9. Click **Yes** on the message.

#### **Calibrating Robot-Mechanical Centering Pickup Position**

The Mechanical Centering centers wafers so that they can be placed in the center of the modules where they are processed. The centering of wafers is especially important for operations involving the Coater and Developer modules.

Keep in mind that calibrating the Mechanical Centering requires the use of a

smallest sized wafer. To calibrate the Mechanical Centering pickup position:

- 1. Place a smallest sized test wafer on the Mechanical Centering.
- 2. From the navigation bar, click System. The System (Robot) page opens.
- 3. For Module, select **Mechanical Centering**.
- 4. For Arm, select either **Cold/Top** or **Hot/Bot**. (*Note: The arms have to be calibrated separately. You can start with either one of them.*)
- 5. Under Training, click Move to Get Position.
- 6. Observe the position of the arm.
- If necessary, adjust the arm position by clicking Move Left, Move Right, Move Up, Move Down, Move In, and/or Move Out until the dot in the center of the test wafer meets the centering dot on the arm.
- 8. When you are about to save the position, move the arm upward slightly until it touches the back of the test wafer.
- 9. Click Save Station Position.

- **10.** Click **Yes** on the message.
- **11.** Repeat Step 4 through 10 to calibrate the other arm.

### **Calibrating Robot-Centering Pickup Position**

The Centering module provides the same function as the Mechanical Centering does — centering wafers. The difference lies in the fact that, while the Mechanical Centering has a clamping mechanism that can automatically sense the size of the wafer placed in it and adjust itself accordingly, the Centering module has a tiered top which means that the user can only place a wafer on the tier that matches its size. Because the Mechanical Centering is more flexible and convenient to use, you most likely will use the Mechanical Centering to center wafers most of the time and use the Centering module only as a backup.

To calibrate the Centering pickup position:

- 1. Place smallest wafer on the Centering module.
- 2. From the navigation bar, click System. The System (Robot) page opens.
- 3. Form Module, select Centering.
- 4. For Arm, select either **Cold/Top** or **Hot/Bot**. (*Note: The arms have to be calibrated separately. You can start with either of them.*)
- 5. Under Training, click Move to Get Position.
- 6. Observe the position of the arm.
- If necessary, adjust the arm position by clicking Move Left, Move Right, Move Up, Move Down, Move In, and/or Move Out until the dot in the center of the test wafer meets the centering dot on the arm.
- **8.** When you are about to save the position, move the arm upward slightly until it touches the back of the test wafer.

#### 9. Click Save Station Position.

- **10**. Click **Yes** on the message.
- **11.** Repeat Step 4 through 10 to calibrate the other arm.

#### **Calibrating Robot-Coater Position**

In order for the Robot to get wafers in and out of a Coater smoothly, you need to calibrate the position of the Robot in reference to that Coater. The goal is to make sure that the Robot and the Coater can work together in sync. The calibration requires that both arms of the Robot be calibrated separately using the same proce-

dures outlined below. Once you are done with the calibration of one Coater module, you can use the same procedures to calibrate the Robot with the other Coaters.

To calibrate the Robot-Coater position:

- 1. Place a wafer on top of the support pins on the Coater.
- 2. From the navigation bar, click System. The System (Robot) page opens.
- **3.** For Module, select **Coater1.** (*Note: The system has more than one Coater module. You can choose to start with any one, but be sure to calibrate them all.*)
- 4. For Arm, select either **Cold/Top** or **Hot/Bot**. (*Note: The arms have to be calibrated separately. You can start with either of them.*)
- 5. Under Training, click Move to Get Position.
- 6. Observe the position of the arm.
- 7. If necessary, adjust the arm position by clicking Move Left, Move Right, Move Up, Move Down, Move In, and/or Move Out.
- **8.** When you are about to save the position, move the arm upward slightly until it touches the back of the test wafer.
- 9. Click Save Station Position.
- 10. Click **Yes** on the message.
- **11.** Repeat Step 4 through 10 to calibrate the other arm.
- **12.** Repeat the above steps to calibrate the position of the Robot in relation to the other Coaters.

#### **Calibrating Robot-Developer Position**

In order for the Robot to accurately get wafers in and out of a Developer module, you need to calibrate the position of the Robot in reference to that Developer. The goal is to make sure that the Robot and the Developer can work together in sync. The calibration requires that both arms of the Robot be calibrated separately using the same procedures outlined below. Once you are done with the calibration of one Developer, you can use the same procedures to calibrate the Robot with the other Developers.

To calibrate the Robot-Developer position:

- 1. Place a wafer on top of the support pins on the Developer.
- 2. From the navigation bar, click System. The System (Robot) page opens.
- **3.** For Module, select **Dev1.** (*Note: The system has more than one Developer module. You can choose to start with any one, but be sure to calibrate them all.*)

- 4. For Arm, select either **Cold/Top** or **Hot/Bot**. (*Note: The arms have to be calibrated separately. You can start with either of them.*)
- 5. Under Training, click Move to Get Position.
- 6. Observe the position of the arm.
- 7. If necessary, adjust the arm position by clicking Move Left, Move Right, Move Up, Move Down, Move In, and/or Move Out.
- **8.** When you are about to save the position, move the arm upward slightly until it touches the back of the test wafer.
- 9. Click Save Station Position.
- 10. Click **Yes** on the message.
- 11. Repeat Step 4 through 10 to calibrate the other arm.
- **12.** Repeat the above steps to calibrate the position of the Robot in relation to the other Developers.

#### **Calibrating Robot-Chill Plate Position**

You need to properly calibrate the position of the Robot in reference to a Chill Plate. The goal is to make sure that the Robot and the Chill Plate can work together in sync so that the Robot can get wafers in and out of the Chill Plate smoothly.

The calibration requires that the two arms on the Robot be calibrated separately using the same procedures outlined below. Once you are done with the calibration of one Chill Plate, you must use the same procedures to calibrate the Robot with the other Chill Plates.

To calibrate the Robot-Chill Plate position:

- 1. Place a wafer on top of the support pins on the Chill Plate.
- 2. From the navigation bar, click System. The System (Robot) page opens.
- **3.** For Module, select **Chill1.** (*Note: The system has more than one Chill Plate module. You can choose to start with any one, but be sure to calibrate them all.*)
- 4. For Arm, select either **Cold/Top** or **Hot/Bot**. (*Note: The arms have to be calibrated separately. You can start with either of them.*)
- 5. Under Training, click Move to Get Position.
- 6. Observe the position of the arm.
- 7. If necessary, adjust the arm position by clicking Move Left, Move Right, Move Up, Move Down, Move In, and/or Move Out.

- **8.** When you are about to save the position, move the arm upward slightly until it touches the back of the test wafer.
- 9. Click Save Station Position.
- 10. Click **Yes** on the message.
- **11.** Repeat Step 4 through 10 to calibrate the other arm.
- **12.** Repeat the above steps to calibrate the position of the Robot in relation to the other Chill Plates.

#### **Calibrating Robot-Hot Plate Oven Position**

You need to properly calibrate the position of the Robot in reference to a Hot Plate Oven. The goal is to make sure that the Robot and the Hot Plate Oven can work together in sync so that the Robot can get wafers in and out of the Hot Plate Oven smoothly.

The calibration requires that the two arms on the Robot be calibrated separately using the same procedures outlined below. Once you are done with the calibration of one Hot Plate Oven, you must use the same procedures to calibrate the Robot with the other Hot Plate Ovens.

For illustration purposes, the following procedures use Hot Plate Oven 1 as an example.

To calibrate the Robot-Hot Plate Oven position:

- 1. Place a wafer on top of the support pins on the Hot Plate Oven 1.
- 2. From the navigation bar, click System. The System (Robot) page opens.
- **3.** For Module, select **Hpo1.** (*Note: The system has more than one Hot Plate module. You can choose to start with any one, but be sure to calibrate them all.*)
- 4. For Arm, select either **Cold/Top** or **Hot/Bot**. (*Note: The arms have to be calibrated separately. You can start with either of them.*)
- 5. Under Training, click Move to Get Position.
- 6. Observe the position of the arm.
- 7. If necessary, adjust the arm position by clicking Move Left, Move Right, Move Up, Move Down, Move In, and/or Move Out.
- **8.** When you are about to save the position, move the arm upward slightly until it touches the back of the test wafer.
- 9. Click Save Station Position.
- 10. Click **Yes** on the message.
- 11. Repeat Step 4 through 10 to calibrate the other arm.
- **12.** Repeat the above steps to calibrate the position of the Robot in relation to the other Hot Plate Ovens.

#### **Calibrating Robot-Vapor Prime Position**

You need to properly calibrate the position of the Robot in reference to the Vapor Prime. The goal is to make sure that the Robot and the Vapor Prime can work together in sync so that the Robot can get wafers in and out of the Vapor Prime smoothly.

The calibration requires that the two arms on the Robot be calibrated separately using the same procedures outlined below.

To calibrate the Robot-Vapor Prime position:

- 1. Place a wafer on top of the support pins on the Vapor Prime.
- 2. From the navigation bar, click System. The System (Robot) page opens.
- 3. For Module, select VPrime.
- **4.** For Arm, select either **Cold/Top** or **Hot/Bot**. (*Note: The two arms must be calibrated separately. You can start with either one as long as you remember to calibrate them both.*)
- 5. Under Training, click Move to Get Position.
- 6. Observe the position of the arm.
- If necessary, adjust the arm position by clicking Move Left, Move Right, Move Up, Move Down, Move In, and/or Move Out.
- **8.** When you are about to save the position, move the arm upward slightly until it touches the back of the test wafer.
- 9. Click Save Station Position.
- **10.** Click **Yes** on the message.
- **11.** Repeat Step 4 through 10 to calibrate the other arm.

## Backing Up and Restoring Robot Configuration

The P9000 is equipped with a pre-calibrated robot which can function in sync with the other system modules with no need for calibration. As a best practice, we recommend that you back up your robot configuration. Doing so will make it easy to restore the original robot settings using the robot configuration backup file if, for some reason, the robot has to be taken out of service for repair or replacement.

#### **Backing Up Robot Configuration**

You can use the following steps to back up the Robot configuration:

To back up the robot configuration:

- **1.** Disconnect the RS232 cable that connects the Robot and the Indexer CPU board.
- **2.** Connect the RS232 cable to V3000 PC COM 1. The Robot now should be directly connected to the V3000 PC.
- 3. Start the Logosol Control Center software on the PC.
- 4. On the Logosol Wafer Handling Control Center Window, click Connection and then Terminal.
- **5.** In the Terminal window, select RS232-COM1-115200 to establish communication with the Robot. See Figure 6-2.



- 6. When the Robot returns the > prompt, enter the following commands (see Figure 6-14):
  - >SOF (Turn off the Robot servo)
  - >.QUIT (Quit the run mode)
- From the Logosol Wafer Handling Control Center window, click File and then File Manger. See Figure 6-3.



FIGURE 6-3: Opening the File Manager

 In the File Manager window, right-click in the right pane and then click New Folder from the pop-up menu. See Figure 6-4.

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	New Open	Ctrl+N Ctrl+O			
	Rename				
	Delete				
	New Folder				
	Send To Target				
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	Error Browser				

#### FIGURE 6-4: Creating a backup folder

- **9.** In the Create new folder dialog box, enter a unique name, e.g., BACKUP, for the folder and click **OK**.
- **10.** Drag and drop the STATION. INI file from the Target directory to the BACKUP directory. See Figure 6-5.

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Host 🔛 BACKUP 💌 💼 🕒	Target CD		•	£			
	Name	Size	Туре	Mo			
	LOADER.INI	1 KB	Target file	29-0			
	ERRORLOG.LOG	14 KB	Target file	08-1			
	PARAMS.INI	2 KB	Target file	11-1			
	H3-GNR.MCX	224 KB	Target file	29-0			
	MCX.INI	1 KB	Target file	05-1			
	PARAMSET.INI	10 KB	Target file	25-0			
	H3-GNRMCX	223 KB	Target file	29-0			
	C&DH3TST.SCP	3 KB	Target file	29-0			
	stats.ini	1 KB	Target file	11-1			
07170	MCX7226R.EXE	348 KB	Target file	29-0			
STATIO	STATIONS.INI	34 KB	Target file	10-1			
	20102000.120	2 KB	Target file	02-0			
	MCXR7223.EXE	340 KB	Target file	30-0			

#### FIGURE 6-5: Dragging STATION.INI file from Target to BACKUP directory

#### **Restoring Robot Configuration**

You can use the following steps to restore the Robot configuration:

1. From the File Manager window, drag and drop the STATION.INI file from the BACKUP directory to the Target directory, as shown in Figure 6-6.

Sa Logosol Wafe	🙀 Logosol Wafer Handling Control Center - [File Manager: CD]									
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				PARAMS.INI	2 KB	Target file	11-10-2006 (			
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				MCX.INI	1 KB	Target file	05-10-2006 (			
				PARAMSET.INI	10 KB	Target file	25-05-2012 *			
				H3-GNRMCX	223 KB	Target file	29-05-2012 *			
				C&DH3TST.SCP	3 KB	Target file	29-05-2012 *			
				stats.ini	1 KB	Target file	11-10-2006 (			
				MCX7226R.EXE	348 KB	Target file	29-05-2012			
				STATIONS.INI	34 KB	Target file	10-10-2006			
				20102000.120	2 KB	Target file	02-02-2012 *			
				MCXR7223.EXE	340 KB	Target file	30-01-2012 -			

FIGURE 6-6: Restoring Robot configuration

- 2. Close the File Manager Window.
- **3.** Execute the following commands (see Figure 6-7):
  - >RUN (Return the Robot to the Run mode)
  - 1549 (Wait until the Robot returns 1549)
  - >SON (Turn the servo on)
  - >HOM (Move the Robot to Home position)



#### FIGURE 6-7: Returning the Robot to Home position

- **4.** After the Robot configuration backup is restored, close the Logosol Wafer Handling Control Center window.
- 5. Disconnect the RS232 cable from the V3000 PC and connect it back to the Indexer CPU board.

#### **Testing the Robot After Restore**

Once you have restored the Robot backup data, the next step is to test the Robot against all the modules individually before putting it into production. The goal is to make sure that the Robot can work smoothly with all the modules. This is especially the case when you have just installed a replacement Robot or when the Robot's configuration is responding incorrectly.

Note that you must test both arms of the Robot individually against all the modules.

To calibrate the Robot:

- 1. Place a cassette with a wafer in it on the Indexer 1.
- 2. From the navigation bar, click System. The System (Robot) page opens.
- 3. On the cassette, select the slot in the Cassette with the wafer in it.
- 4. For Module, select Indexer1.

- **5.** For Arm, select an arm, e.g., Cold/Top. (*Note: You can start with either arm, but you do need to test both arms with Indexer 1 separately.*)
- 6. Under Control, click Get, Put, and Centering, one at a time.
- 7. Observe the operation of the Robot at each action to see if it works properly.
- 8. If the Robot works smoothly with Indexer 1, move on to test other modules, one by one, by repeating Steps 4 through 7; if the Robot does not work well with Indexer 1 as desired, calibrate it using the procedures discussed earlier in this chapter, test it again until you have achieved the desired result, and then move on to test other modules.

## Centering Coaters/Developers

The procedures for centering Coater and Developer modules are the same. The P9000 comes with multiple Coater and Developer modules, each of which must be centered individually using the following procedures. The goal of centering the Coater and Developer modules is to make sure that wafers are properly centered on the chuck while being processed.

The procedures for centering the Coater or Developer involve both the Robot and the Coater or Developer. For illustration purposes, the following instructions use Coater 1 as an example.

To center the Coater:

- 1. Place a cassette with wafers on the Indexer station.
- 2. From the navigation bar, click System.
- **3.** Click **OK** on the message. The default System (Robot) page opens. See Figure 6-1.
- 4. For Module, select **Indexer 1** (or **Indexer 2**), depending on which one you want to use.
- 5. For Arm, select **Cold** or **Hot**, depending on which one you want to use.
- 6. Select a wafer size, e.g., Big Wafer.
- 7. Select Mechanical Centering.
- 8. On the Cassette, select a slot with a wafer in it.

**9.** Under Control, click **Get.** The Robot moves to the Get position to pick up the wafer from the selected slot on the cassette. Figure 6-8 illustrates Steps 1 through 9



FIGURE 6-8: Centering the Coater module

- **10.** From the top of the screen, click the Coater 1 tab.
- 11. Under Control, click **Put.** The Robot moves the wafer to the Centering and then Coater 1.
- 12. Under Training, click Move to Get Position.
- 13. Under Vacuum, click Vacuum On.
- 14. Under Training, click **Move Up** to move the arm upward until the wafer clears the top of the three pins.
- **15.** From the top of the System page, click the Coater1 tab to open the Coater 1 page.
- 16. Under Support Pins, click Bottom.
- **17.** Place the centering tool on top of the Coater 1 chuck.
- **18.** Insert the three diagnostic pins into the holes in the top of the centering tool.

- **19.** Click the Robot tab.
- **20.** Move the arm down slowly until the wafer fits inside the perimeter of the three pins. If necessary, move the arm in or out, or left or right until the wafer does not touch any of the pins.
- **21.** When everything is clear, move down until the wafer is inside the three pins and touches them all.
- **22.** Move the wafer up to get the centering tool out.
- **23.** Click the Coater 1 tab to open the Coater 1 page.
- 24. Under Support Pins, click **Top.** See Figure 6-9.

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					_					Diam Arm	1 mm			

FIGURE 6-9: Centering the Coater

- **25.** Click the Robot tab to move back to the Robot page.
- Under Training, click Move Down until the wafer sits on top of the support pins.
- 27. Under Vacuum, click Vacuum Off.
- 28. Click Save Station Position.
- **29.** Click **Yes** on the message.
- **30.** Remove the wafer from Coater 1.
- **31.** Repeat the above steps to calibrate the other Coater modules and the Developer modules.

## Centering Chill Plates

Unlike the centering of Coater and Developer modules which requires that you center each module individually using the same procedures, the centering of the Chill Plate only requires the centering of Chill Plate 1. Because the Chill Plate modules come as a stack, once Chill Plate 1 is properly centered, the system will automatically apply the settings to the rest of the Chill Plate modules. To center the Chill Plates:

- 1. On the System page, make sure the Robot tab is selected.
- 2. For Module, select Chill1.
- 3. For Arm, select Hot/Bot or Cold/Top, depending on which one you prefer.
- 4. Under Training, click Move to Get Position.
- 5. Click **Disable Torque** so that you can manually move the arm out.
- **6.** From the top of the page, click the Chill1 tab to open the Chill 1 page. See Figure 6-10.
- 7. Under Move 3Pins, click **Bottom** to move the three support pins to the bottom position.

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ndexer1	👅 Indexer2 🥌 Coater	1 Scoater2	S Dev1	Dev2	🥌 VPrime	🗢 Нро 1	🗢 Нро2	🗢 НроЗ	<ul> <li>Hpo4</li> <li>Diagnost</li> <li>Va</li> <li>3P</li> </ul>	Chill Chil2 tic Sensors: acuum
	Vacuum Vacuur Vacuur	n On n Off		ve 3Pins To Boti	om P	3			Service Servic	Yins Bottom

- **8.** Place the centering tool on top of the Chill Plate chuck, making sure that the tool and the top of the chuck engage with each other.
- **9.** Manually move the arm in until it touches the back of the centering tool. (If the arm hits the centering tool, move the arn up.)
- **10.** From the top of the page, click the Robot tab to return to the Robot page. Refer to Figure 6-8.
- **11.** Click **Enable Torque.** This will make the system remember the position of the centering tool.
- 12. Move the arm up to remove the centering tool from the Chill Plate.
- 13. Place a wafer on top of the arm.
- 14. From the top of the page, click the Chill 1 tab to return to the Chill 1 page.
- **15**. Under Move 3Pins, click **Top.**

- 16. From the top of the page, click the Robot tab to return to the Robot page.
- 17. Under Training, click **Move Down** until the wafer touches the support pins.
- 18. Click Save Station Position.
- 19. Click **Yes** on the message.

### Centering the Hot Plate Ovens

The P9000 can come with multiple Hot Plate Oven modules, which must be centered individually using the same procedures described below.

For illustration purposes, the following procedures use Hot Plate Oven 1 as an example.

To center the Hot Plate Oven 1:

- 1. From the navigation bar, click System.
- 2. Click **OK** on the message. The System page opens.
- 3. From the top of the System page, click the Hpo1 tab.
- 4. Under Support Pins, select **3 Pins Bottom**. Figure 6-11 illustrates Steps 1 through 4.



FIGURE 6-11: Centering the Hot Plate Oven

- 5. From the top of the System page, click the Robot tab to open the Robot page. Refer to Figure 6-8.
- 6. For Module, select **Hpo1**.
- 7. For Arm, select **Top/Hot** or **Cold/Bot**.
- 8. Under Training, click Move to Get Position.
- 9. Click Disable Torque.
- 10. Place the centering tool on top of Hot Plate 1.
- **11.** Manually move the arm in until it touches the back of the centering tool. (Note: If the arm hits the centering tool, move the wafer up.)
- 12. Click Enable Torque.
- **13.** Under Training, click **Move Up** until the arm clears the centering tool enough to take it (centering tool) out.
- 14. From the top of the page, click the Hpo1 tab.
- 15. Under Support Pins, click **3 Pins Up**.
- 16. From the top of the page, click the Robot tab.
- **17.** Place a wafer on the arm.
- 18. Under Training, click **Move Down** until the top of the pins levels with the arm.
- 19. Click Save Station Position.
- 20. Repeat the above steps to calibrate Hpo2, Hpo3, and Hpo4.

### Centering the Mechanical Centering

The Mechanical Centering is used to align wafers to make sure that wafers are properly centered and aligned with the arm. It is important to note that you must use the smallest- sized wafer to center the Mechanical Centering.

To center the Mechanical Centering:

- 1. From the navigation bar, click System.
- 2. Click **OK** on the message. The Robot page opens. Refer to Figure 6-8.
- 3. For Module, select Mechanical Centering.
- 4. For Arm, select an arm of your choice, e.g., Cold/Bot.
- 5. Select the smallest wafer size.
- 6. Place a smallest-sized wafer on the Mechanical Centering you are centering.
- 7. Under Training, click **Move to Get Position**.

- **8.** From the top of the page, click the Mechanical Centering tab to open the Mechanical Centering page.
- 9. Click **Centering In.** See Figure 6-62.



FIGURE 6-12: Centering the Mechanical Centering

- 10. From the top of the page, click the Robot tab to return to the Robot page.
- 11. Under Training, click **Move Up** until the arm touches the wafer.
- 12. Under Vacuum, click Vacuum On.
- **13.** From the top of the page, click the Mechanical Centering tab to move to the Mechanical Centering page.
- Click Home. The wafer now sits on the arm because of the suction of the vacuum.
- **15.** From the top of the page, click the Robot tab to return to the Robot page.
- 16. Under Training, click **Move Up** until the wafer clears the Mechanical Centering.
- 17. Click **Disable Torque**.
- 18. Manually move the arm out to see if the wafer is centered.
- **19.** If the wafer is not centered, make a note of the amount of deviation and continue with Steps 20 thorough 25.
- **20.** Remove the wafer from the arm.
- 21. Click Enable Torque.
- 22. Click Move to Home Position.
- 23. Click Move to Get Position.
- 24. Put the wafer back on the Mechanical Centering and center it by clicking Move In, Move Out, Move Left, and/or Move Right as needed until the wafer is perfectly centered.
- 25. Click Save Station Position.

# Calibrating the Centering

Calibration of the Centering module is to ensure that wafers are properly centered when they are being processed. It is important to note that calibrating the Centering module must be done using the smallest-sized wafer.

To calibrate the Centering module:

- 1. Place a smallest-sized wafer on the Centering module.
- 2. From the navigation bar, click System.
- 3. Click **OK** on the message. The Robot page opens.
- 4. For Module, select **Centering**.
- 5. For Arm, select an arm option, e.g., Cold/Bot.
- 6. Select the smallest wafer size.
- 7. Under Training, click Move to Get Position.
- 8. Under Vacuum, click Vacuum On.
- 9. Under Training, click **Move Up** until the wafer clears the centering tool.
- 10. Select Centering.
- 11. Click **Disable Torque.**
- **12.** Manually move the arm out to check the result: If the dot in the center of the testing wafer matches the dot on the arm, then it is centered; otherwise, continue calibrating the Centering module using the above procedures until the two dots meet.

#### 13. Click Save Station Position.

### Calibrating Support-Pin Height

The height of the support pins on the Hot Plate Oven and the Vapor Prime modules must be properly calibrated. The goal is to set the support pins' 0 (zero) position.

For illustration purposes, the following instructions use Hot Plate Oven 1 (Hpo1) as an example. You can use the same procedures to calibrate the support-pin height on the other Hot Plate Oven and the Vapor Prime modules.

To calibrate the height of the support pins on Hot Plate Oven 1:

- 1. From the navigation bar, click System.
- 2. Click **OK** on the message. The System page opens.

- 3. From the top of the System page, click the Hpo1 tab.
- 4. Under Support Pins, click **3 Pins Bottom**.
- 5. Inspect the height of the pins in reference to the surface of the Hot Plate Oven.
- 6. If the pins stick out (higher than the surface of the module), click **Move Down** to **Position** until the top of the pins levels with the surface of the Hot Plate Oven.
- 7. Click Save Pins 0 Position.
- 8. Click **Yes** on the message. See Figure 6-13.

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CED Connected 10/29/2012 Count: 1641 5:38:57 PM CommetPro P9 SEMICONDUCTOR C PLEASE RESET SYSTEM TO INITIALIZE.	Name: CDAdmin Role: Super User Logon: 0000:03:13:45	e Maintenance
🖝 Robot 📨 Indexer1 📨 Indexer2 🥯 Coater1 🥯 Coater2 🧐 Dev1 🧐 Dev2 🥌 VPrime	Hpo1 🗢 Hpo2 🗢 Hpo3 🥌 Hpo4	Chil1 Chil2
Vacuum Support Pins Lid Cover	Teaching Data Diagnos	tic Sensors:
Vacuum On 3 Pins Top Lid Up	Backup 😡 Va	icuum
	<u>●</u> 3F	Pins Top
Vacuum Off 3 Pin Bottom Lid Down	G Restore	ins Bottom
	🥯 Li	d Cover Top
	🕒 Lic	d Cover Bottom
Temperature Move 3 Pins	Calibration	eat Over Temp.
Set Temperature 25 °C Move Up To Pos.	Calib 3 Fins Steps Save pins 0 position	erature: 25.80 (°C) Gap: 11.0 (mm)
Primware version: B01-011E Main System Recipes Datalog Setur	eset	ownload hogram Marathon

FIGURE 6-13: Calibrating height of support pins

## Checking Vapor Prime Operations

From time to time, you need to check the function of the vacuum gauge and the HMDS to ensure the proper operation of the Vapor Prime module. The procedures involve the Chamber Vacuum (the Vacuum Gauge and the Regulator) and the HMDS Canister.

At all times, the HMDS canister pressure must be above the pre-configured settings. You can adjust the HMDS Canister pressure by turning the Regulator knob (clockwise or counter-clockwise).

To check the function of the Vapor Prime:

- 1. From the navigation bar, click the System button.
- 2. Click **OK** on the message. The Robot page opens.
- 3. For Module, select **Indexer 1** or **Indexer 2**, depending on which one you want to use.
- 4. For Arm, select **Cold/Top**.
- 5. Select a wafer size.
- 6. On the cassette, select a slot in the Indexer with a wafer in it
- 7. Under Control, click Get.
- 8. For Module, select VPrime
- 9. Select Centering or Mechanical Centering.
- 10. Under Control, click Put.
- **11.** From the top of the page, click the VPrime tab.
- 12. Click **Download Program.**
- **13.** Select the program of interest.
- 14. Click Download.
- 15. Click Start. See Figure 6-14.

SmartPro P9000 - Build 20	12.10.26 - 18.10 (CoreMultiV	Vafer2_1)			
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SERVICES. INC.	PLEASE RESE	T SYSTEM TO INITIA	LIZE. <b>12</b>		
🖝 Robot 📨 Indexer1	👅 Indexer2 🥌 Coater1	🗢 Coater2 🥌 Dev1 🥌	Dev2 🥌 VPrime 📥 Hpo1	🧠 Нро2 🥌 Нро3 🕴	🗢 Hpo4 🗢 Chill1 🗢 Chill2 🕕
Vacuum	Support Pins	Lid Cover		Teaching Data	Diagnostic Sensors:
Vacuum On	3 Pins Top	Lid Up		Backup	Vacuum
Vacuum Off	3 Pin Bottom	Lid Down		Restore	3Pins Top
					3Pins Bottom
Gases					Lid Cover Top
N2 On E	chaust On Chamber V	sc. On			Heat Over Temp.
N2 Off E	chaust Off Chamber V	ac. Off			
Temperature		Move 3 Pins		Calibration	Temperature: 25.00 (°C)
Set Temperature	25 °C	Move Up To Pos.		Calib 3 Pins Steps	Gap: 0.0 (mm)
		2.0			
		3.0 mm		Save pins 0 position	
	(16)	Move Down To Pos.			13
	Start (1)	Stop 间 Abr	ort 🕝 Reset		Download Program Marathon
Firmware version: B01-0111				U	
🙆 Main	System	Recipes Datalog	g 😣 Setup	Alarms	Silence 🕢 Help



- **16.** Verify the achieved vacuum levels during the pump down cycle. Systems with proximity pin hotplates should achieve 8 to 12 inches of vacuum; systems with vacuum contact hotplates should achieve 15 to 18 inches of vacuum. Contact the factory immediately if the vacuum levels fall outside these ranges.
- **17.** Turn on the HMDS and check if the vacuum level is rising. (*Note: Normally, the vacuum level should be rising due to the pressure of the HMDS.*)
- **18**. From the top of the page, click the Robot tab.
- 19. Under Control, click Get.
- 20. For Module, select Indexer1.
- 21. Under Control, click Put.

## Checking Hot Plate Oven Exhaust

Checking the exhaust level on a Hot Plate Oven requires the use of a manometer. The goal is to ensure that the module can discharge the appropriate amount of exhaust.

To check the exhaust on a Hot Plate Oven:

- 1. Remove the plug on the exhaust.
- 2. Connect the Manometer by inserting the tube into the exhaust vent.
- 3. Adjust the butterfly valve until an ideal exhaust volume has been reached.
- 4. Remove the manometer.
- 5. Put the plug back in.

### Checking Coater/Developer Exhaust with Controller

You can check the exhaust on a Coater or a Developer with a controller using the procedures discussed below. For illustration purposes, the following instructions use Coater 1 as an example.

To check the Coater exhaust with the controller:

- 1. From the navigation bar, click System.
- 2. Click **OK** on the message. The System page opens.
- 3. From the top of the System page, click the Coater1 tab.
- 4. Under Support Pins, click Bottom.
- **5.** Place the Manometer on top of the Developer or Coater to cover the entire exhaust.
- 6. From the navigation bar, click Recipe. The Programs & Recipes page opens.
- 7. On the Programs & Recipes page, click the Module Options tab.
- 8. From the left side of the page, click Coater 1.
- 9. For Exhaust Control On/Off, set the value to 1 (i.e., On).
- 10. For Idle Exhaust Value, first set the low value for the exhaust band, e.g., 10.
- 11. Click Save.
- **12**. Click **Yes** on the message.
- **13.** Click **Download** and check the Manometer to see if the reading matches the value you set.

- 14. Repeat Steps 9 through 13, with Idle Exhaust Value set to a high value of 80.
- **15.** If the exhaust is out of band, re-calibrate the exhaust controller until you have reached the desired value.

### Checking Coater/Developer Exhaust Without Controller

You can also check the exhaust on a Coater or a Developer without a controller using the instructions outlined below. An Anemometer is required in order to perform the procedures.

For illustration purposes, the following instructions use Coater 1 as an example.

To check the Coater exhaust without the controller:

- 1. From the navigation bar, click System.
- 2. Click **OK** on the message. The System page opens.
- 3. From the top of the System page, click the Coater1 tab.
- 4. Under Support Pins, click Bottom.
- 5. Seal the Coat/Develop bowl in such a way that an Anemometer can be used to reliably measure the air flow.
- 6. Adjust the butterfly valve until you have got the ideal exhaust volume.
- **7.** Repeat the same procedures to check the exhaust on all Coater and Developer modules.

# Checking Coater/Developer Low Spin Speed

For Coaters and Developers, the low spin speed is 100 RPM. Checking the low spin speed of a Coater or a Developer requires the use of a spin-test wafer and an optical Tachometer. The spin-test wafer comes with a reflector that allows the Tachometer to read the spin speed. The following instructions use Coater 1 as an example, but the same procedures can be applied to all Coater and Developer modules.

To check the low spin speed of Coater 1:

- 1. Place a cassette with the spin-test wafer it on the Indexer station.
- 2. From the navigation bar, click System.
- 3. Click Yes on the message. The System (Robot) page opens.

- 4. For Module, select **Indexer1** or **Indexer2**, depending on which has the cassette with the spin-test wafer in it.
- 5. For Arm, select an arm of your choice.
- 6. Select a wafer size that matches the size of the spin-test wafer.
- 7. Select Mechanical Centering or Centering.
- 8. On the cassette, select the slot that contains the spin-test wafer.
- 9. Under Control, click Get.
- 10. For Module, select Coater1.
- **11.** Under Control, click **Put.** The system first puts the spin-test wafer into the Centering (or Mechanical Centering) module and then onto Coater 1.
- **12.** From the top of the page, click the Coater1 tab.
- 13. Under Vacuum, click Vacuum On.
- 14. Under Support Pins, click Bottom.
- **15.** Under Spindle Spin, set the value to 100.
- 16. Click Spin.
- **17.** Place the Tachometer on top of the spin-test wafer to check the spin speed: If the reading is less than or equal to +/- 3 RPM, it is acceptable; if the reading is greater than +/ -3 RPM, contact C&D Semiconductor for correction.
- **18.** Click **Stop.** Figure 6-15 highlights Steps 12 through 16 and 18.
- **19.** Remove the spin-test wafer and the Tachometer.



FIGURE 6-15: Checking Coater 1 low spin speed

## Checking Coater/Developer High Spin Speed

For Coater or Developer modules, any spin speed greater than 3,000 RPM is considered a high spin speed. Checking the high spin speed of a Coater or Developer also requires the use of a spin-test wafer, which has a reflector that allows the Tachometer to read the spin speed. The following instructions use Coater 1 as an example, but the same procedures can be applied to all Coater and Developer modules.

To check the high spin speed of Coater 1:

- 1. Place a cassette with the spin-test wafer it on the Indexer station.
- 2. From the navigation bar, click System.
- 3. Click Yes on the message. The System (Robot) page opens.
- 4. For Module, select **Indexer 1** or **Indexer 2**, depending on which has the cassette with the spin-test wafer in it.
- 5. For Arm, select an arm of your choice.
- 6. Select a wafer size that matches the size of the spin-test wafer.
- 7. Select Mechanical Centering or Centering.
- 8. On the cassette, select the slot that contains the spin-test wafer.
- 9. Under Control, click Get.
- **10.** For Module, select Coater 1.
- 11. Under Control, click **Put.** The system first puts the spin-test wafer into the Centering (or Mechanical Centering) module and then onto Coater 1.
- **12.** From the top of the page, click the Coater 1 tab.
- 13. Under Vacuum, click Vacuum On.
- 14. Under Support Pins, click Bottom.
- 15. Under Spindle Spin, set the value to 3,500.
- 16. Click Spin.
- **17.** Place the Tachometer on top of the spin-test wafer to check the spin speed: If the reading is less than or equal to +1 or 1, it is acceptable; if the reading is greater than +1 or -1, contact C&D Semiconductor for correction.
- 18. Click Stop.
- **19.** Remove the wafer and the Tachometer.

# Checking the Developer Air Ring Gap

The air ring refers to the white raised circular lip around the chuck of a Developer module, as illustrated in Figure 6-16. The air ring gap is the distance between the bottom of a wafer and the air ring. Measuring the air ring gap requires the use of a feeler gauge. You can check the air ring gap on every Developer using the procedures discussed below. The goal is to make sure that the air ring gap is within the manufacturer's specification. For illustration purposes, the following instructions use Developer 1 as an example.



FIGURE 6-16: Checking Developer air ring gap

To check the air ring gap on a Developer module:

- 1. Place a cassette with wafers in it on an Indexer module.
- 2. From the navigation bar, click System.
- 3. Click Yes on the message. The System (Robot) page opens.

- 4. For Module, select **Indexer 1** or **Indexer 2**, depending on which Indexer you have chosen to use in Step 1.
- 5. For Arm, select an arm of your choice.
- 6. Select a wafer size, making sure that it matches the size of wafer in the cassette.
- 7. Select Mechanical Centering.
- 8. On the Cassette, select the slot with a wafer in it.
- 9. Under Control, click Get.
- **10.** For Module, select Developer 1.
- 11. Under Control, click Put.
- **12.** From the top of the page, click the Developer 1 tab.
- 13. Under Support Pins, click Bottom.
- 14. Under Vacuum, click Vacuum On.
- **15.** Use a feeler gauge or other similar devices to measure the gap between the wafer and the air ring. (*Note: It must measure 0.030 inches (0.762 mm), +/-0.005 inches (0.127 mm).*
- 16. Once you have finished checking the air ring gap, click Vacuum Off.
- 17. For Support Pins, click **Top.**
- **18.** Remove the wafer from Developer 1.

# Checking Hot Plate Oven/Vapor Prime Temperature

The operation of Hot Plate Oven and Vapor Prime modules has strict temperature requirements. To ensure the proper performance of these modules, you must make sure that current temperature match the set temperature on the WATLOW using the following procedures, which can be applied to all Hot Plate Oven and Vapor Prime modules.

For illustration purposes, the following instructions use Hot Plate Oven 1 as an example.

To check Hot Plate Oven 1 temperature:

- 1. From the navigation bar, click System.
- 2. Click Ok on the message. The System (Robot) page opens.
- **3.** From the top of the page, click the Hpo1 tab.
- 4. Under Support Pins, click **3 Pins Bottom.**

- 5. Place the thermometer on Hot Plate Oven 1.
- 6. Check the readings on the thermometer.
- 7. Look at the temperature readings on the WATLOW, as shown in Figure 6-17.



FIGURE 6-17: Temperature readings on WATLOW

**8.** If the reading on the thermometer is above the set value on the WATLOW, adjust upward; if the reading on the thermometer is below the set value on the WATLOW, adjust downward.

## Calibrating the WATLOW

The WATLOW must be properly configured to function well. The WATLOW panel comes with a number of control buttons for configuring the WATLOW, as highlighted in Figure 6-18.





To set up the WATLOW:

- 1. Hold down the up and down arrow buttons simultaneously for six seconds to enter the SETUP page: [A1][SET]
- 2. Press the Advance button once: [XX][SEn], where XX= input type (tc = thermocouple).
- **3.** Calibrate the offset input to compensate for lead wire resistance by holding down the arrow buttons simultaneously for approximately three seconds to enter the OPERATION page: [Ai][OPEr]
- **4.** Press the Advance button three times: [X.X][1.CA], where X.X = offset value, e.g., -1.0 degree or 0.6 degree.

#### Note:

For more information, refer to the WATLOW User's Manual (PM PID J. pdf).

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# **APPENDIX A**

# **Energy Isolating Devices-**

1	DC P.S 1 OUTPUT 24VDC 14 AMP
2	CIRCUIT BREAKER 1 POLE DIN MOUNT AIC/5,000 A
3	TRANSFORMER, DUAL PRI 24V SEC
4	CIRCUIT BREAKER, 3POLE 15 AMP AIC/5,000 A @ 277 VAC
5	FUSE 3 AG 1/2 AMP SLO BLO
6	CIRCUIT BREAKER 2P 7AMP AIC/5,000 A @ 277 VAC

FOR REFERENCE ONLY

### **Hazardous Energy Isolation**

De energize AC at the Spindle Controller On/Off White Button De energize DC Power –this can be done by the Green Power Button



Spindle Controller



Green Power Button

## Solid Waste

As a result of the operation of the P9000 System, solid waste can be captured in the Drain Jar located in the bottom portion of the tool and requires Pumping out or Draining depending on the customer's application or preference. There are sensors which inform the user if the capture is too high. It is the responsibility of the end user to respond to the alarms appropriately and timely for the safety of the tool and operators.

The image below shows the location and the Containment method. Refer to the Preventive Maintenance Manual for further information.



Drain Jar



### **APPENDIX B**

## SYSTEM INTERLOCKS REFERENCE TABLE

	MODULE	DESCRIPTION(INTERLOCK)	PURPOSE	ACTION TAKEN	SAFETY
	SYSTEM				
		SYSTEM NZ SENSOR	TO MONITOR PROPER N2 IS SUPPLIED TO TOOL	FINISH CURRENT WAFER, NO NEW WAFER WILL BE PROCESSED	
N		DOOR INTERLOCK (OPTIONAL)	TO MONITOR ALL DOORS ARE CLOSED	FINISH CURRENT WAFER, NO NEW WAFER WILL BE PROCESSED	
-		SySTEM EXHAUST SENSOR	TO MONITOR PROPER SYSTEM MODULE EXHAUST	FINISH CURRENT WAFER, NO NEW WAFER WILL BE PROCESSED	AUDIBLE ALARM SOUNDS, DISPLAY IDENTIFIES EXHAUST OUT OF BAND
I	ROBOT	1			
F		ROBOT VACUUM SENSOR	MONITORING OF BOTH END-EFFECTORS	NO TRANSFERING OF WAFERS ARE POSSIBLE	
-	COATER				
R		DRAIN HI-LEVEL SENSOR	MONITORING OF COATER WASTE	FINISH CURRENT WAFER, NO NEW WAFER WILL BE PROCESSED	NO FURTHER DISPENSING OCCURS UNTIL DRAIN JAR IS EMPTIED
		WAFER CHUCK VACUUM SENSOR	MONITORING OF PROPER VACUUM ON WAFER	IMMEDIATE STOP ON COATER	
L		WALKENDER PREDOW SENSOR			
~		EBR CANISTER LEVEL LOW SENSOR	MONITORING OF EBR LEVEL	FINISH CURRENT WAFER, NO NEW WAFER WILL BE PROCESSED	
0		PHOTO-RESIST LEVEL LOW SENSOR	MONITORING OF LEVEL ON P/R BOTTLES	FINISH CURRENT WAFER, NO NEW WAFER WILL BE PROCESSED	
С	DEVELOPER				
К		WAFER CHUCK VACUUM SENSOR	MONITORING OF PROPER VACUUM ON WAFER	IMMEDIATE STOP OF DEVELOPER FUNCTION	
Ċ		DEVELOP CANISTER LEVEL LOW SENSOR	MONITOR PROPER LEVEL OF CANISTER	FINISH CURRENT WAFER, NO NEW WAFER WILL BE PROCESSED	
2	HPO PLATE OVE	N			
		TEMP. OUT OF BAND	TO MONITOR CURRENT TEMP. IS IN ALLOWED BAND	FINISH CURRENT WAFER, NO NEW WAFER WILL BE PROCESSED	OVER TEMP SWITCH ENGAGES SHUTTING DOWN WATLOW HEATER
	VAPOR PRIME				
		V/P CANISTER LOW LEVEL SENSOR	MONITORING OF HMDS LEVEL IN CANISTER	FINISH CURRENT WAFER, NO NEW WAFER WILL BE PROCESSED	
		TEMP. OUT OF BAND	TO MONITOR CURRENT TEMP. IS IN ALLOWED BAND	FINISH CURRENT WAFER, NO NEW WAFER WILL BE PROCESSED	OVER TEMP SWITCH ENGAGES SHUTTING DOWN WATLOW HEATER
		HMDS FLOW SENSOR	VERIFICATION OF VAPOR FLOW	FINISH CURRENT WAFER, NO NEW WAFER WILL BE PROCESSED	
		WAFER VACUUM SENSOR	MONITORING OF VACUUM ON CHILL PLATE	FINISH CURRENT WAFER, NO NEW WAFER WILL BE PROCESSED	

REVISION	AUTHOR	REASON /CHANGES	APPROVALS	DATE RELEASED
А		INITIAL RELEASE		11/12/2012
В	MPR/L.TRUONG	COMPLY WITH SEMI S2,CHGS. REGARDING SAFETY, SYSTEM ON/OFF PROTOCOLS, ADD ALARMS TABLE, ADD APPENDIX, A/B, SCREEN CAPTURES UPDATED AND TERMINOLOGY OF MECH /FUNNEL CENTERING ESTABLISHED. ADDED NOTE: MANDATORY WFR ON CHUCK, VERIFY AIR RING LEVEL.	C&D Review Board (Proxy)	2/4/2014